

# A 2D slope measuring system based on Stitching Shack Hartmann optical head

**Guillaume Dovillaire**

Samuel Bucourt – Xavier Levecq

**Imagine Optic**

France

**Mourad Idir**

Shinan Qian - Konstantine Kaznatcheev

***midir@bnl.gov***

***BNL/NSLS II***

Collaboration



NSLS II



# Outline

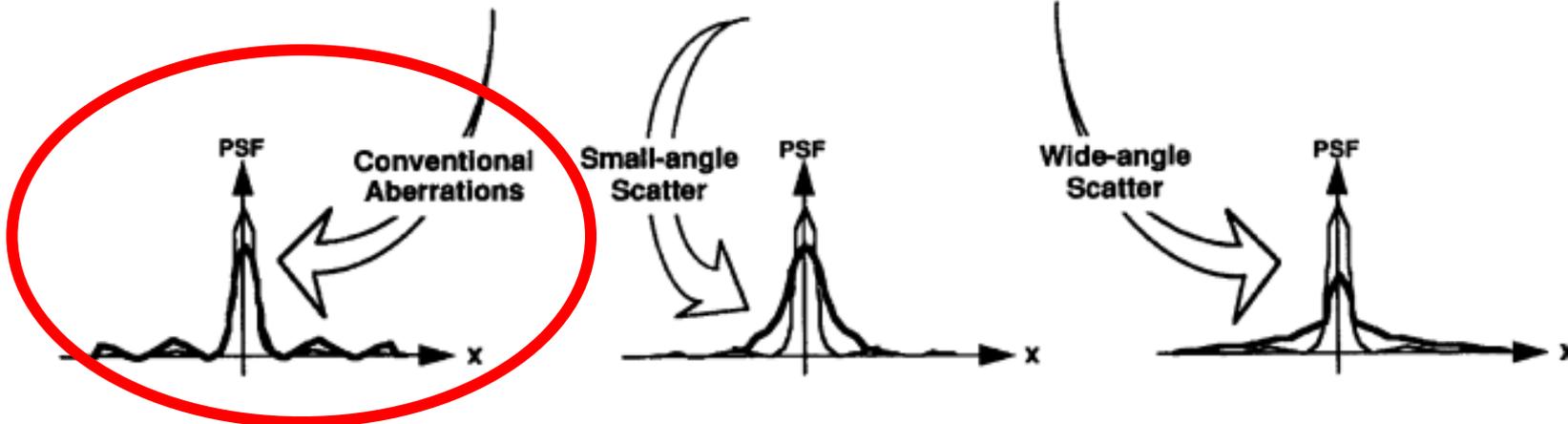
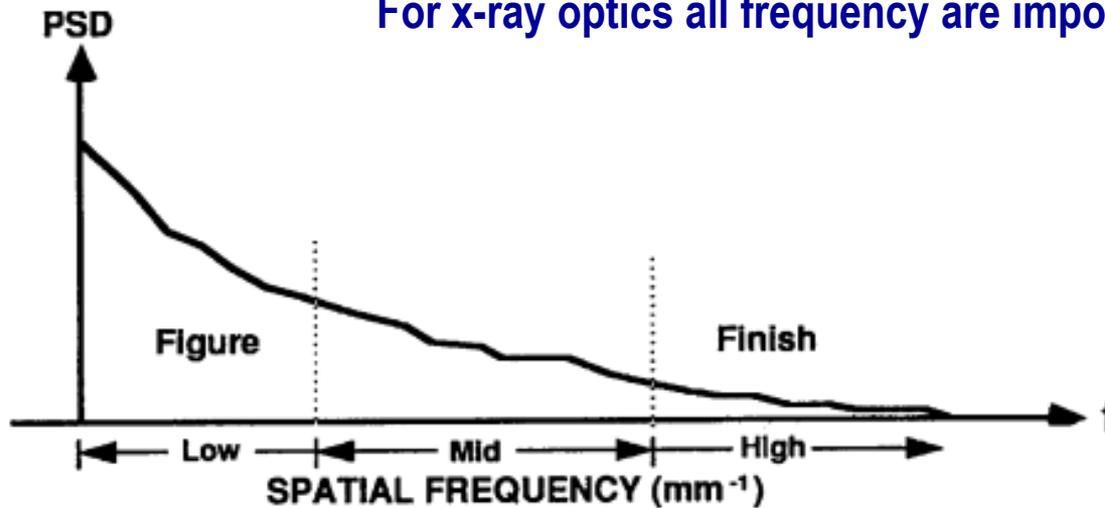
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- **Optical Head Description**
- ***First results***
- ***Possible improvements***
- **Summary**

# Metrology requirements

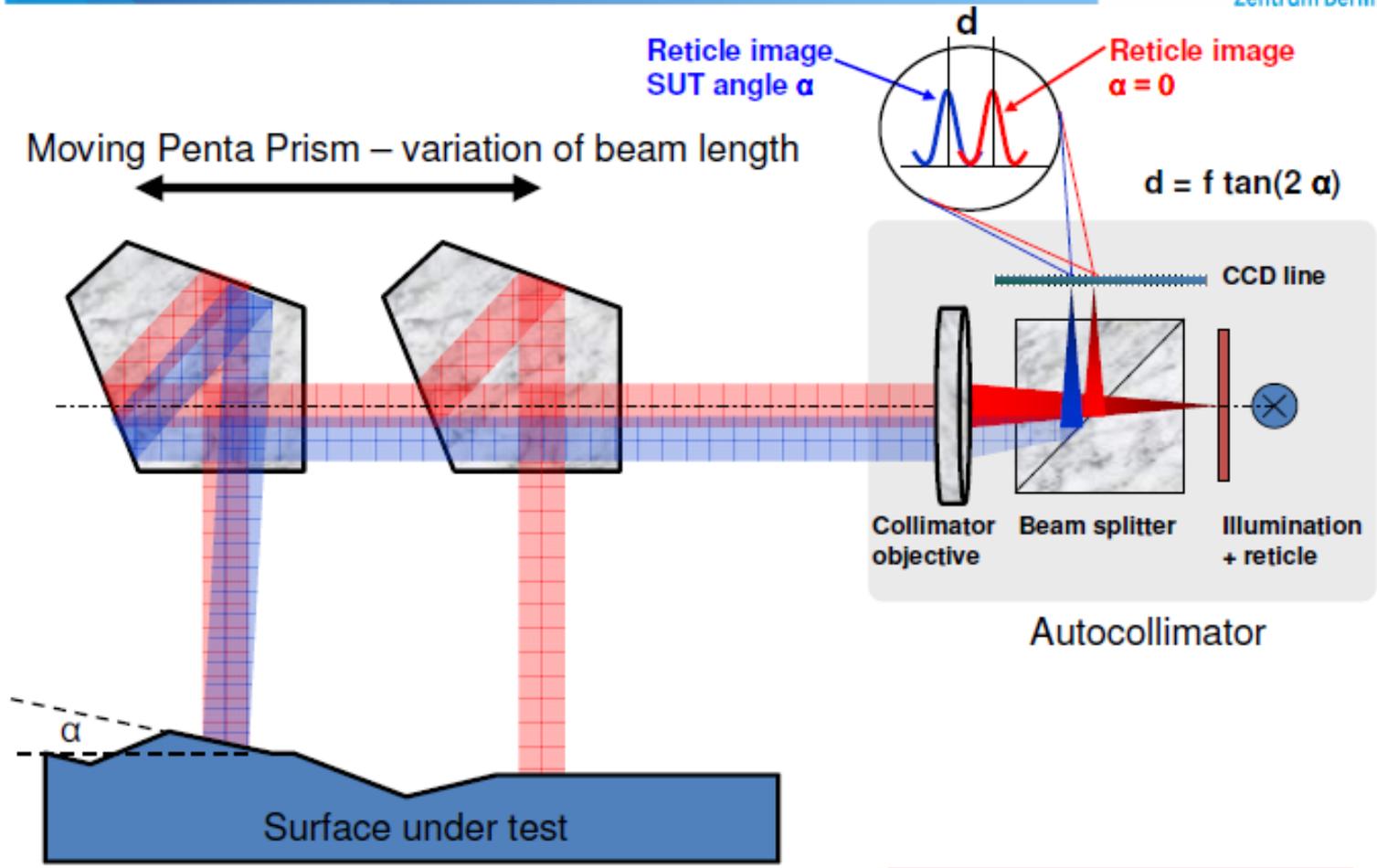
Effect of the surface quality differs on each spatial frequency regime

For x-ray optics all frequency are important



# Deflectometry based Optical Metrology Station NOM type System

How to measure Optics ? – let`s take the Slopes !

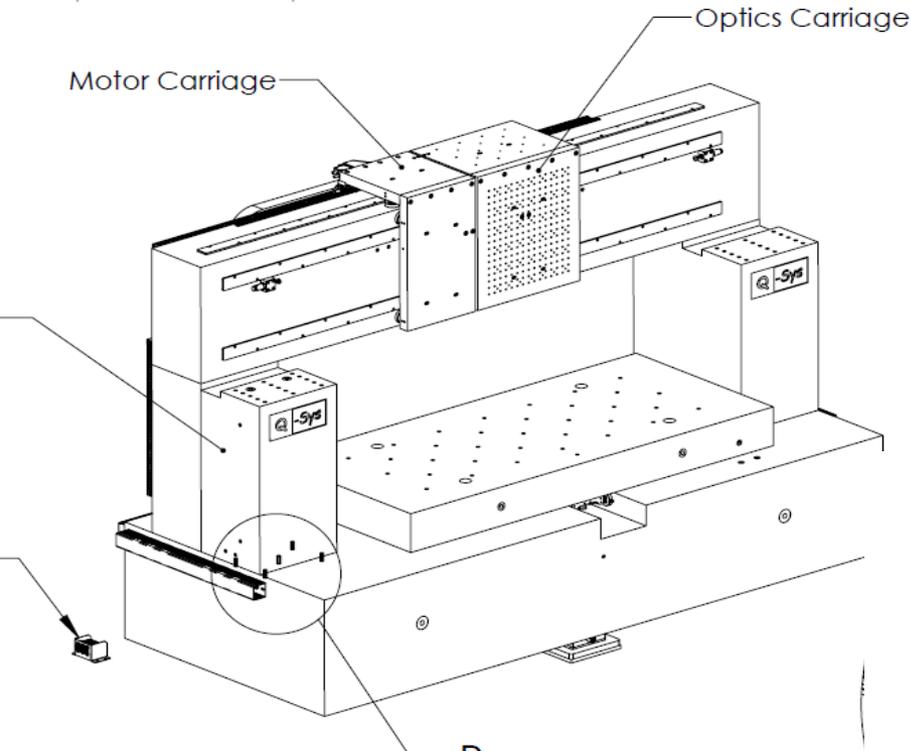


Diamond Light Source, ACTOP 2011 4<sup>th</sup> - 5<sup>th</sup>, April 2011

F. Siewert, BESSY-II / INT / Optical Metrology

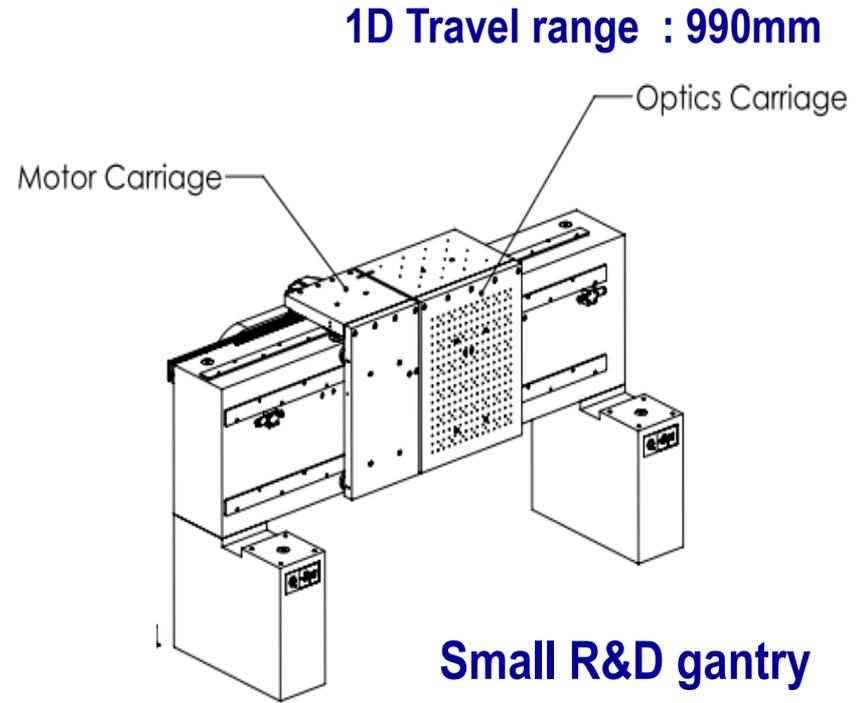


# Deflectometry based Optical Metrology Station

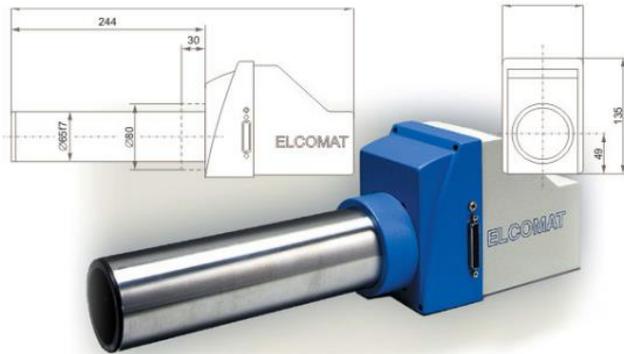


**Big 2D gantry**

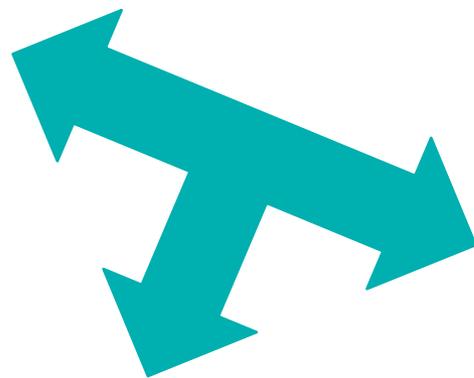
**2D Travel range : 1500 mm**



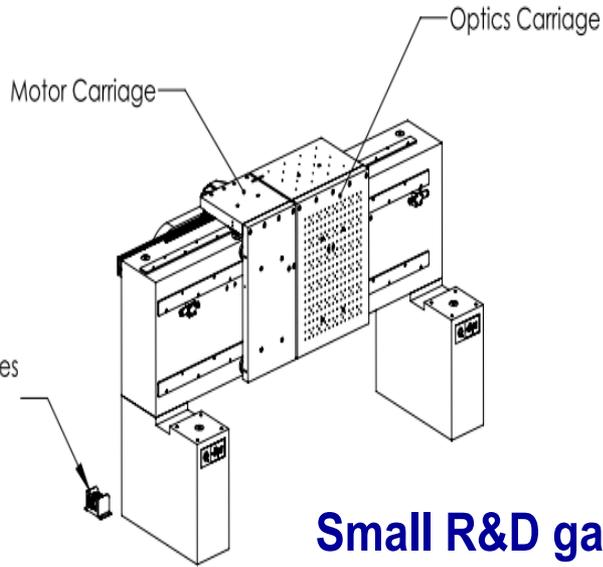
ELCOMAT 3000



High accuracy Autocollimator



1D Travel range : 990mm

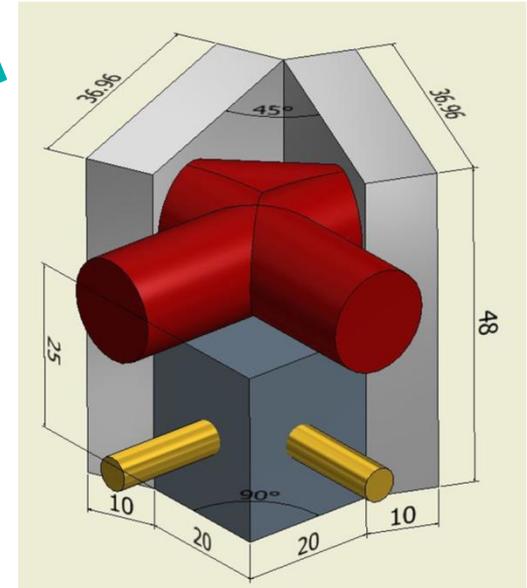


Small R&D gantry



Henry Over  
Philipp Wallington

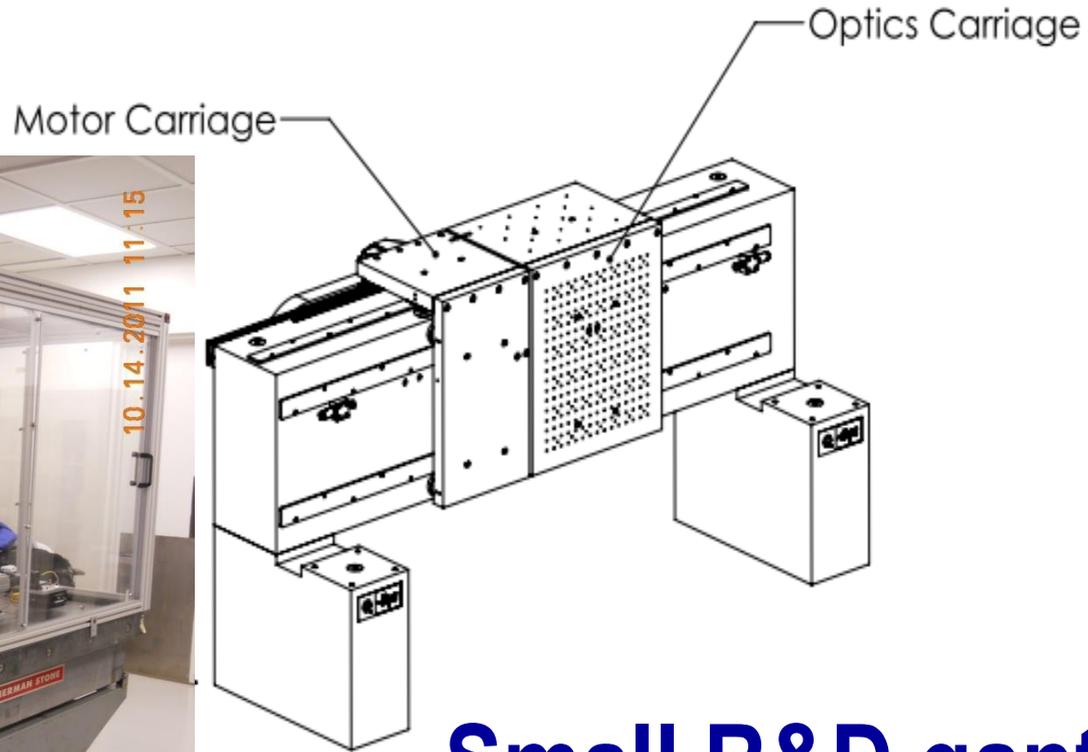
Stable and accurate Motion system



Hollow penta-prism  
20 x 20 mm

# Deflectometry based Optical Metrology Station

Travel range : 990mm

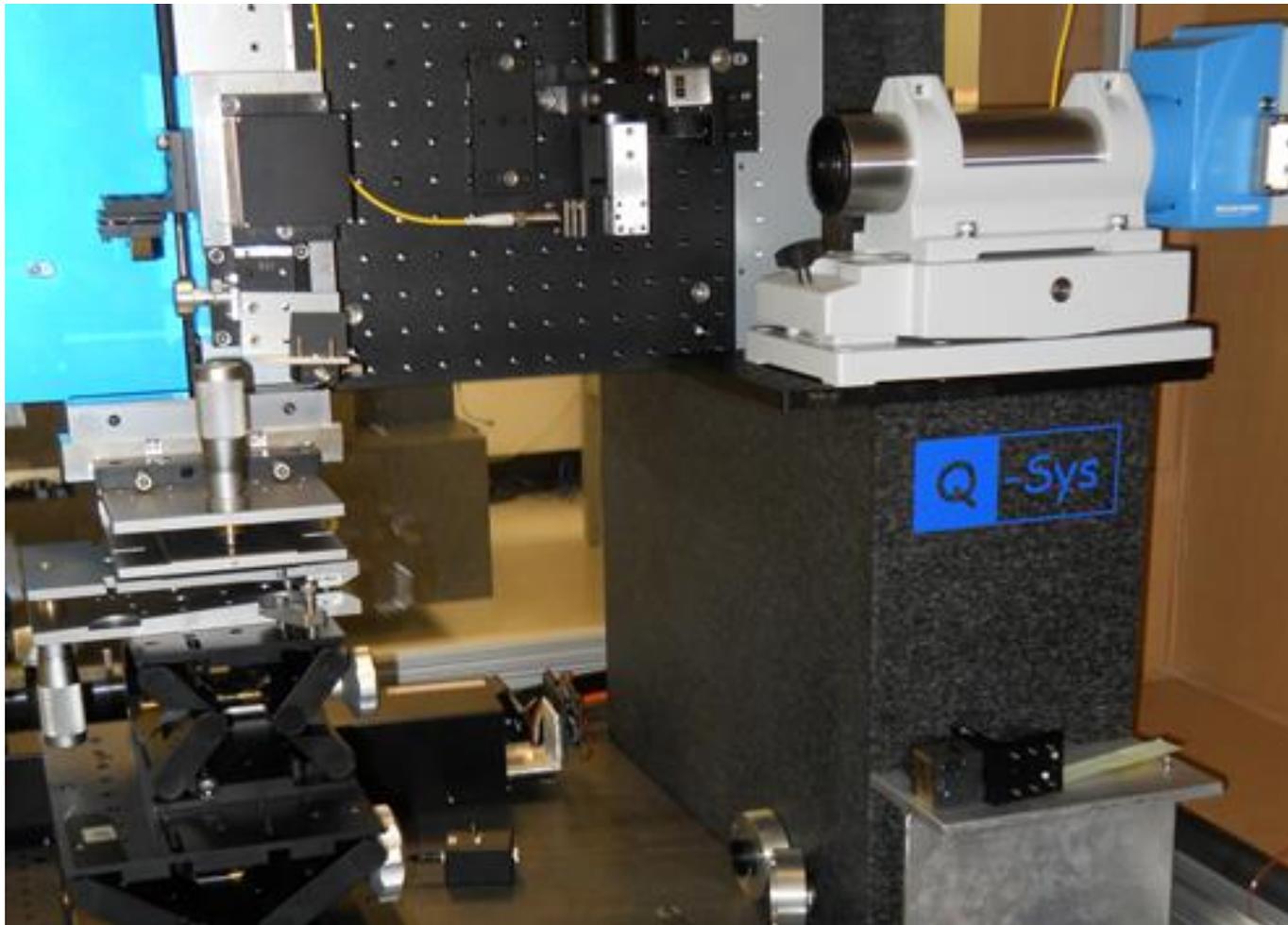


## Small R&D gantry



# Deflectometry based Optical Metrology Station

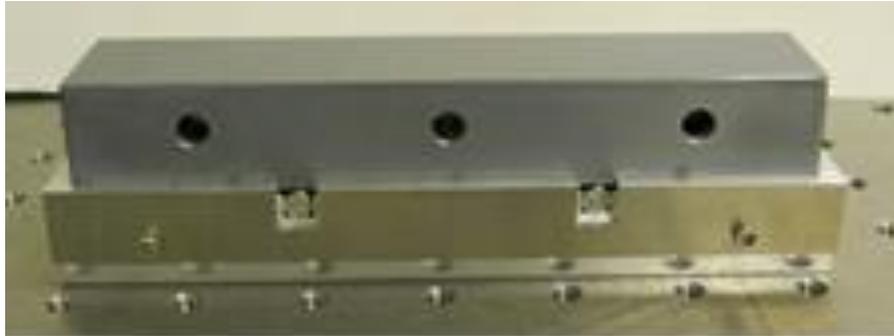
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# Deflectometry based Optical Metrology Station

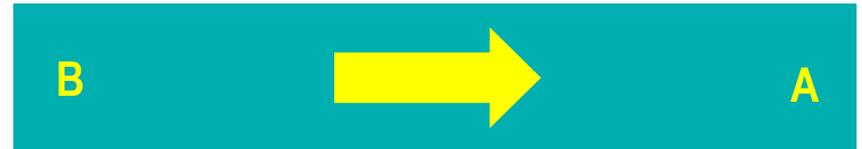
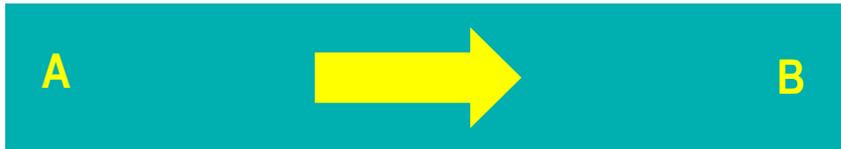
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## Flat Silicon mirror



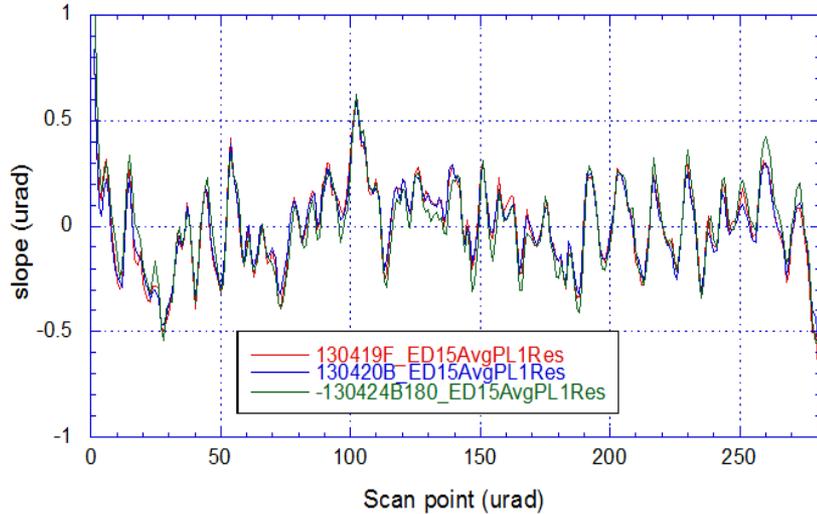
Size: 150 mm x 30 mm x 23 mm

Shape: flat    Material: silicon



*See Shinan's QIAN poster*

#1 Mirror tests: forward, backward & 180° rotation scans on different days tested on 04/19, 04/20 & 04/24/13, 15 scans & 50 points average for each curve 1st order polynomial is removed, slope errors: **0.194**, **0.181** and **0.198** urad rms.



Two forward scans separated in one month and on the mirror shifted for 100 mm residual slope error 41 nrad, 1st order polynomial is removed Tested on 03/12/13, 10 scans & 60 points average and 4/19/13, 15 scans & 50 points average

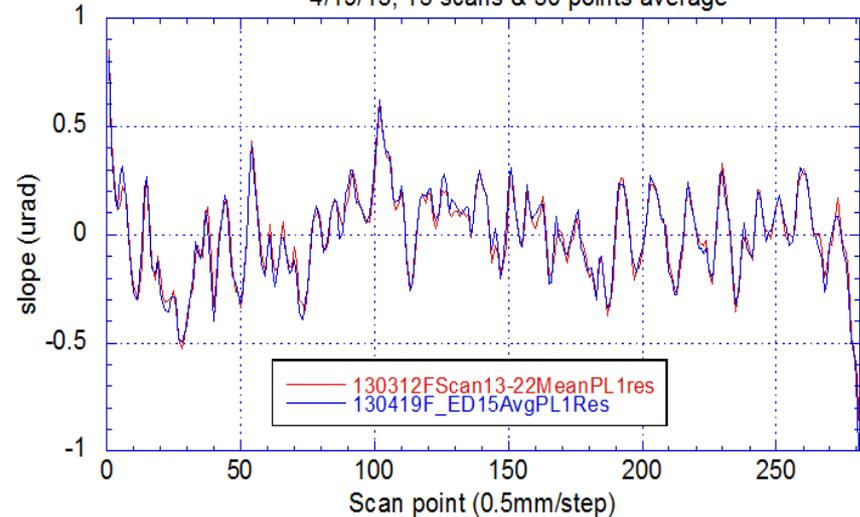


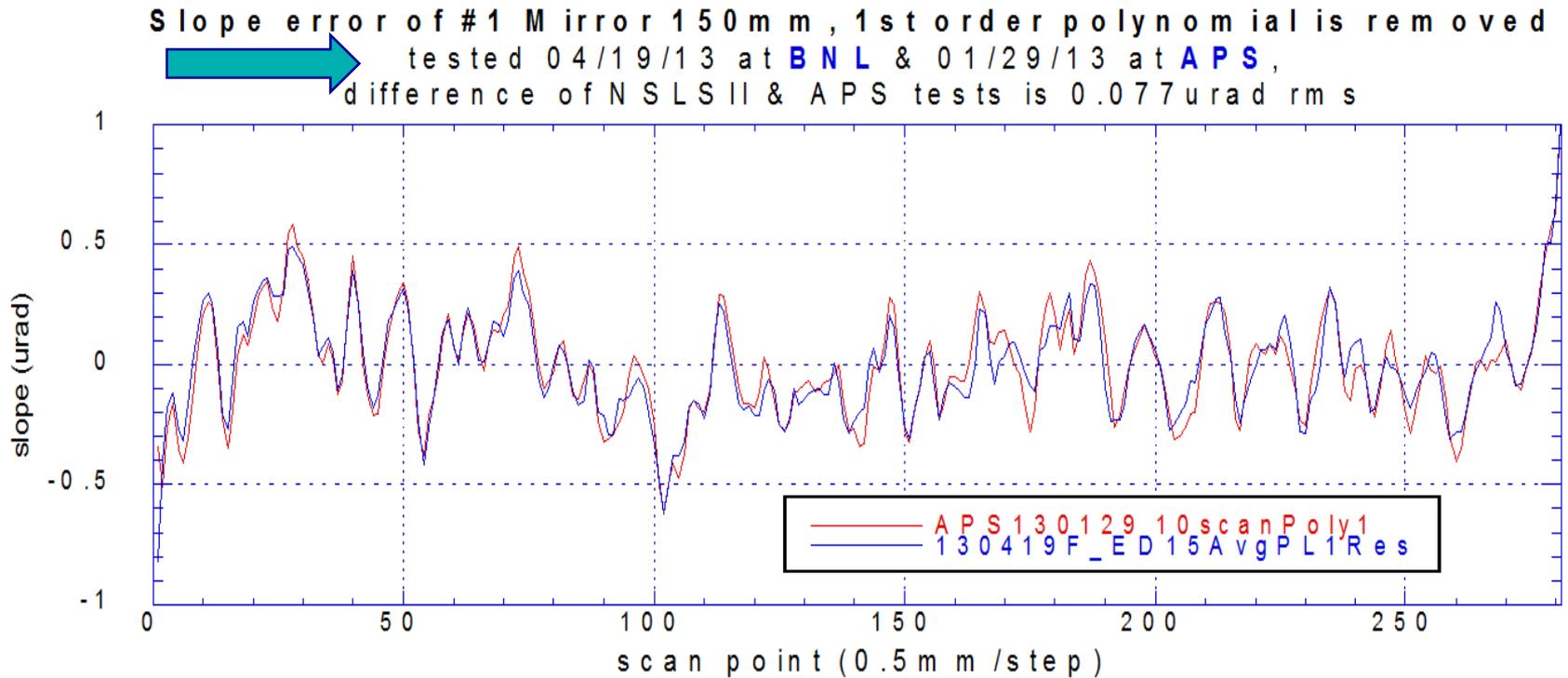
Fig.7 #1 Mirror tests: forward, backward and 180°-rotation scans

Fig. 8 Two forward scans in one month, mirror shifted 100 mm

Different scans	15 scans	F-B	F-R	B-R	F-FM & shift 100mm
Repeatability (nrad rms)	75	35	61	63	41

# NSLS II NOM – APS NOM

Shinan Qian  
Lahsen Assoufid – J Qian (APS)



Comparisons of #1 mirror 150mm with NSLSII-NOM1 and APS-NOM tested on 4/19/13 and 1/29/13, error 77nrad rms

## Height error difference is 0.3 nm rms

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# A 2D slope measuring system based on Shack Hartmann optical head

# Deflectometry based Optical Metrology Station

## NOM type machine : Design

Parameter	Specification
Platform dimensions [mm]	2600(w)x 1100(d)x1700(h)
Platform weight [kg]	5500
Electrical supply voltage and load	230Vac 5A rms
Electrical supply type	50/60 Hz single phase
Air supply pressure	6 – 7 bar
Air consumption	30 l/min
Air dew point	-20 degC at 1 bar



**Optical Platform**  
~ 200 kg

Travel has been maximized at 1500 mm

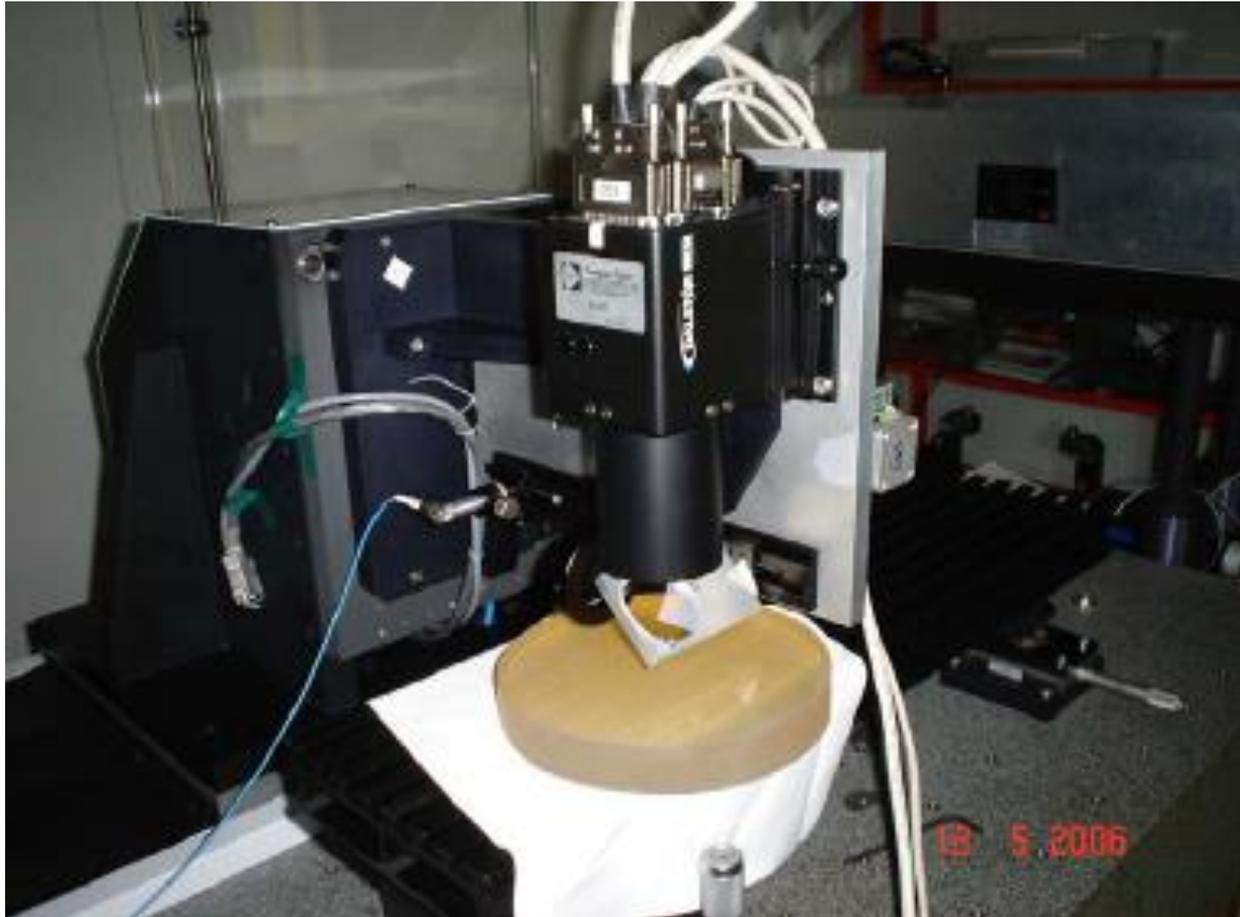


**Optical Head**  
~ 25 kg



# Deflectometry based Optical Metrology Station

Stitching Shack Hartmann head for Long Trace Profiler : SSH-LTP



*From Muriel Thomasset / SOLEIL*

Imagine Optic/France

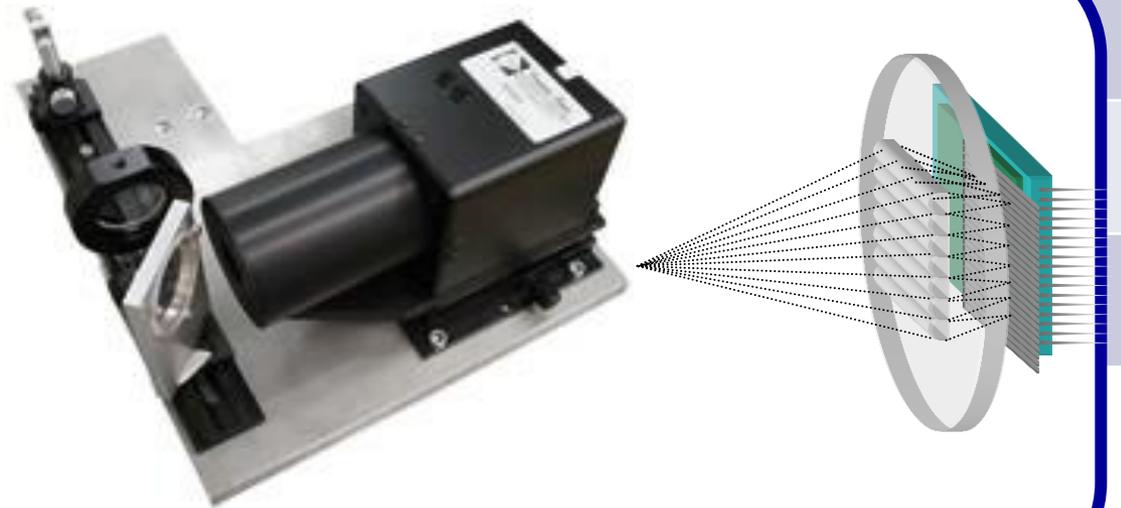
# Stitching Shack-Hartmann Wavefront system Concept

**Problem** : Measured 1.5 meter long mirror with 50nm rms accuracy, highest possible spatial resolution with mirror radius as low as possible.

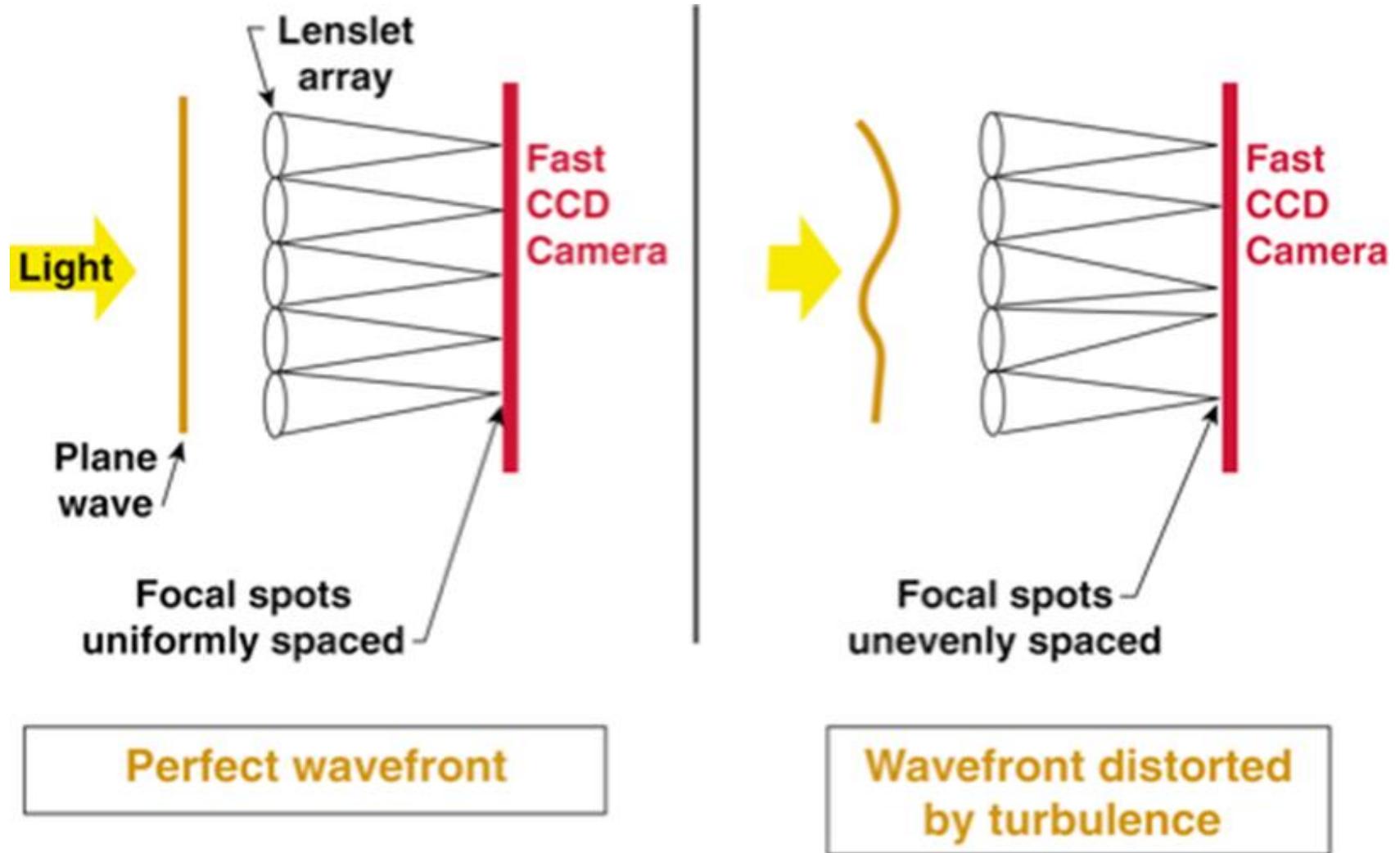
## **Solution** :

1. very sensitive wavefront sensor +
2. source +
3. translation stage +
4. stitching algorithm

Shack-Hartmann Wavefront sensor	
Number of points	15 x 11
Pupil size	18 x 13 mm

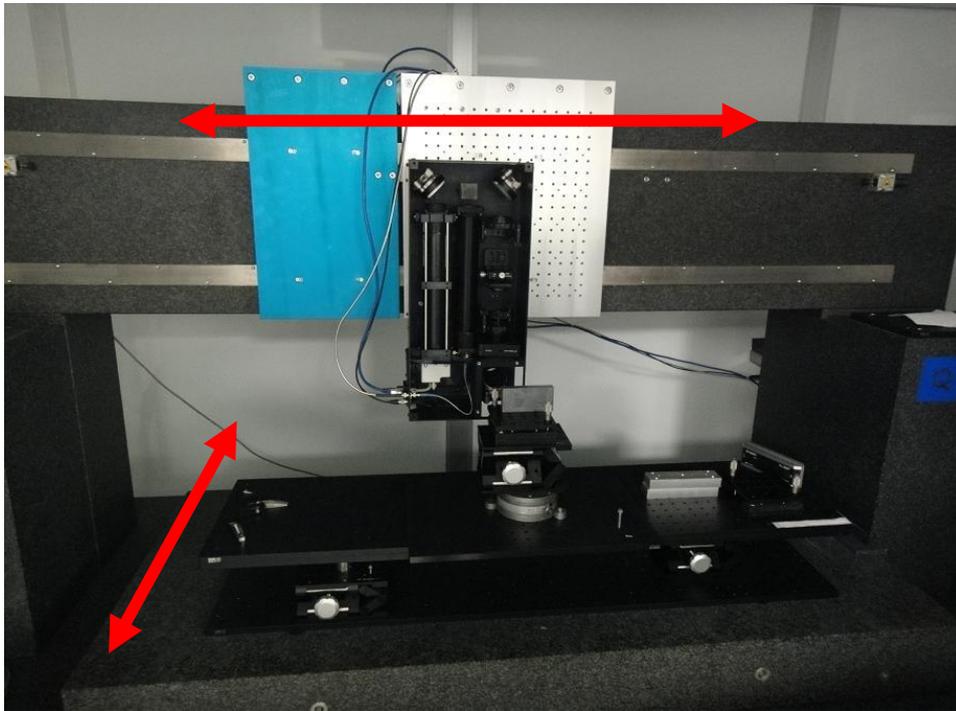


# Shack-Hartmann Wavefront sensor Concept



# Stitching Shack Hartmann Optical Head : SSHOH

System installed at BNL



System as designed

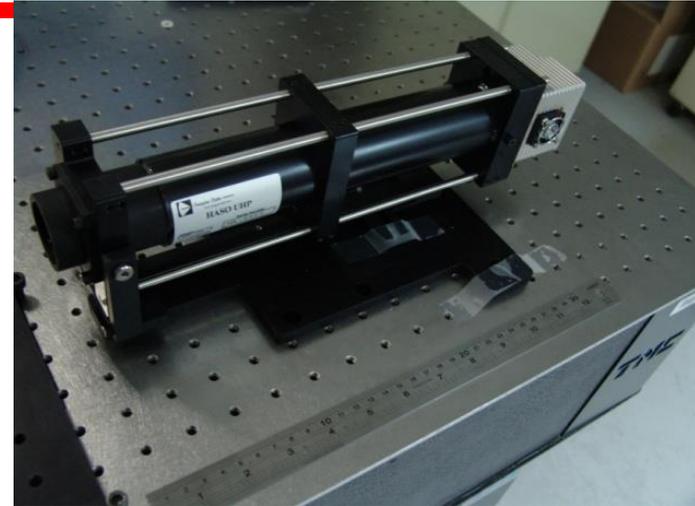


Collaboration between  *Imagine Optic* (France) and NSLS II

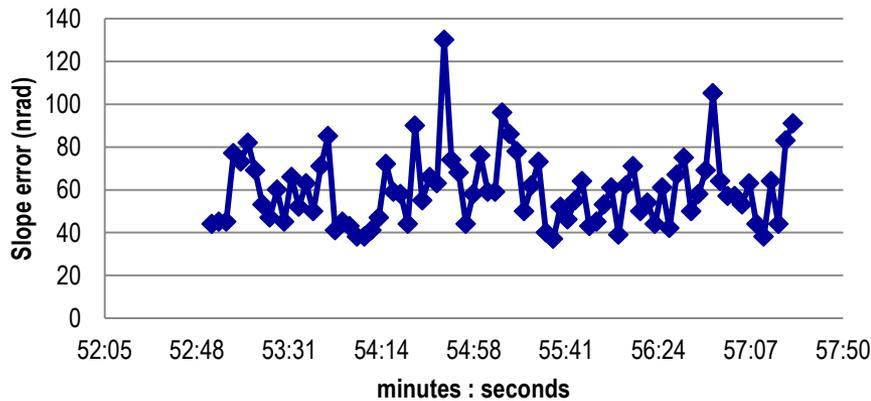
Gantry from 

# The wavefront sensor

Shack-Hartmann Wavefront sensor	
Number of points	15 x 11
Microlenses size	1.2 x 1.2 mm <sup>2</sup>
Sensitivity	Down to 40 nrad rms

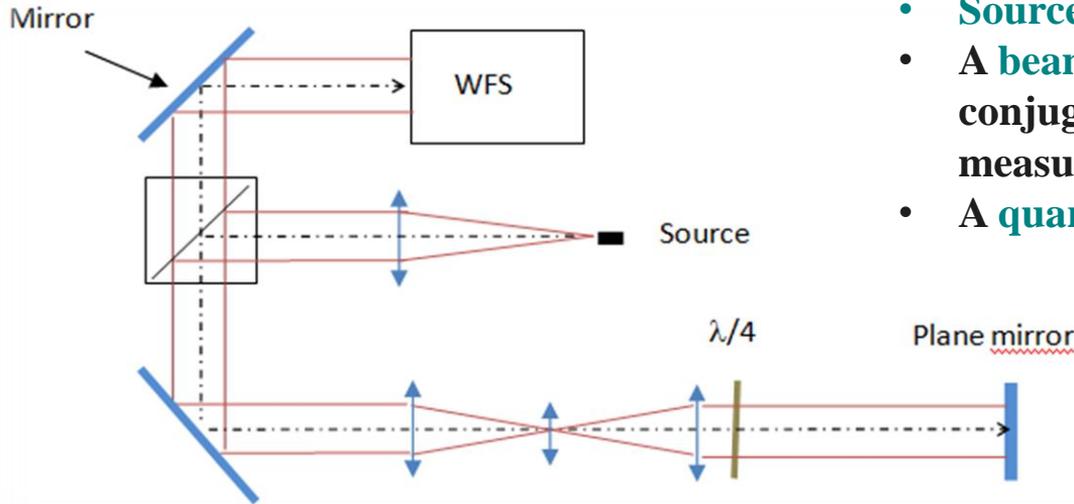


HASO UHP sensitivity (10x100ms)

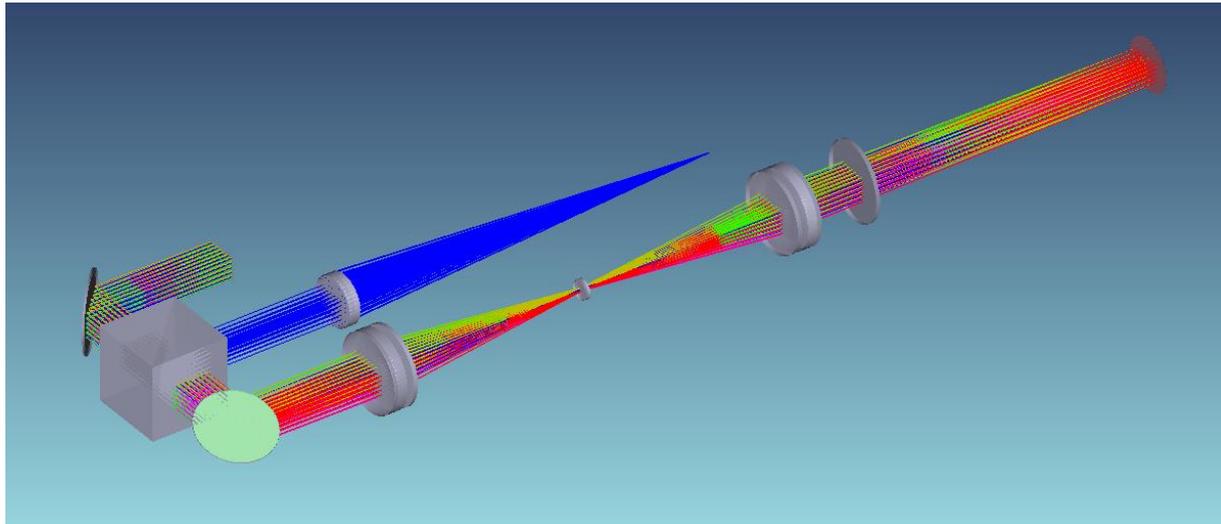


**The impact of air turbulences is very important.**  
**Averaging 10 images allows to reach 40nrad rms...**

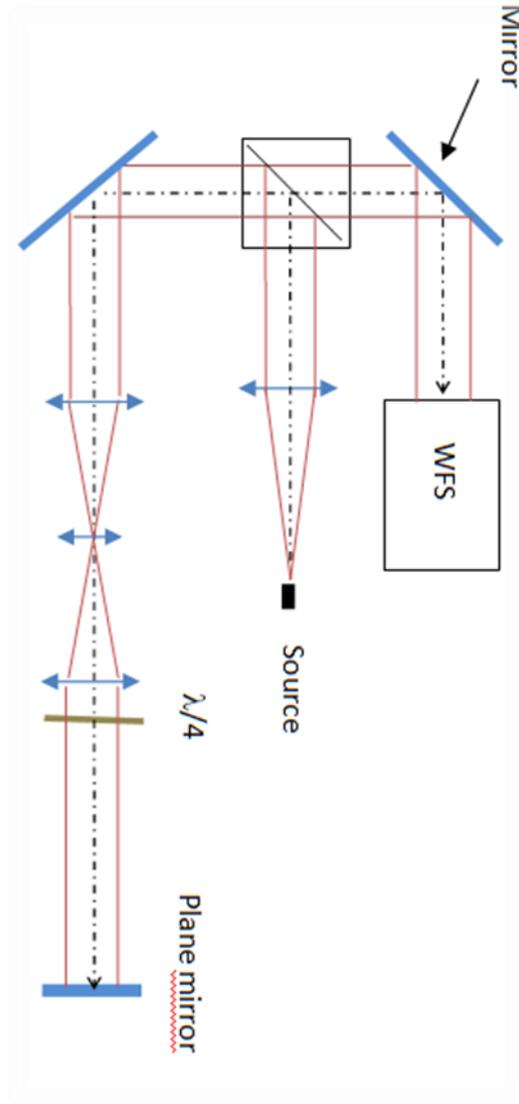
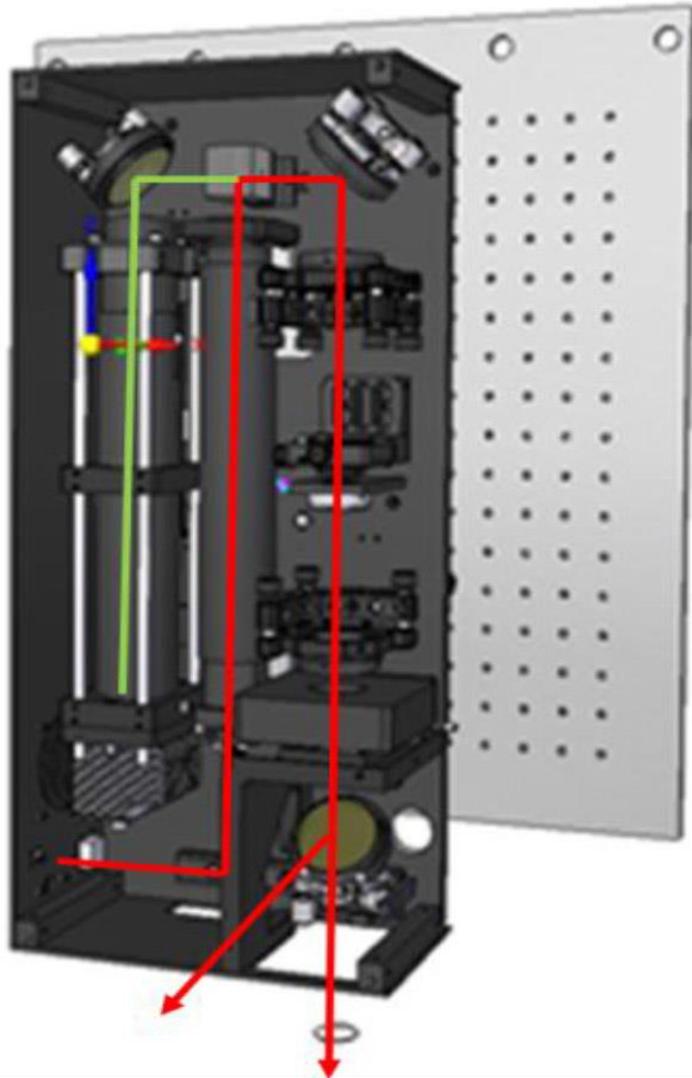
# The source and pupil imaging



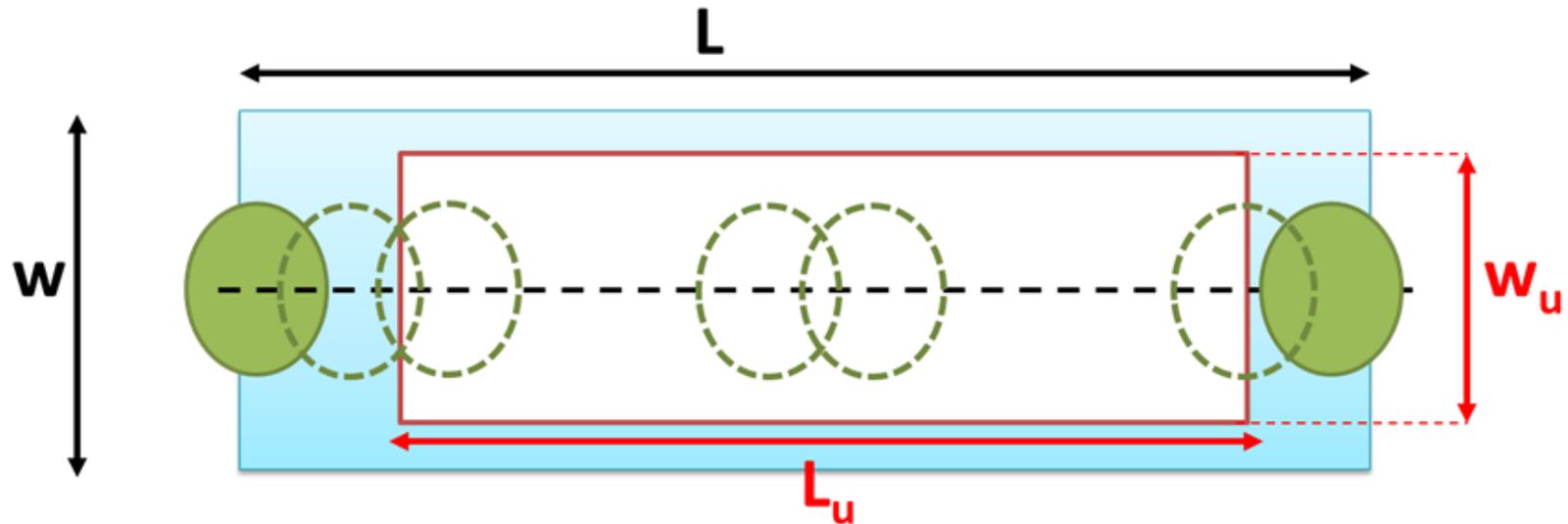
- **Source** is a fibered laser diode at 405 nm.
- A **beam expander** (magnification = -1) allows a conjugation between the mirror under measurement and the microlenses array
- A **quarter wave** is needed to remove all ghosts



# The mechanical design



# Measurement principle



SSH-OH pupil 18 x 13 mm spatial resolution 1.2 mm

## Stitching principle and SSH-OH parameters

# The Stitching algorithm

Needed to remove the translation stages errors and build the entire surface map



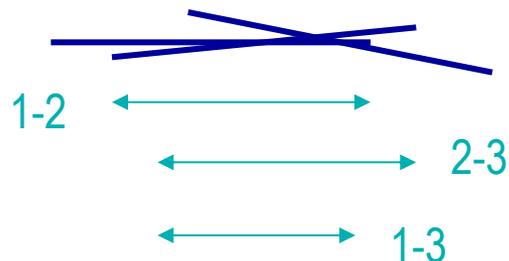
.....



On the overlap area : the measured slopes must be the same



Translation stages errors can be calculated by measuring the tilts in all the common areas



As there are many overlap areas, the algorithm uses all these data to calculate the best possible stages errors (LSM approach) that explains all the measured differences in these common areas

Translation errors are then subtracted to the raw data and data are finally averaged

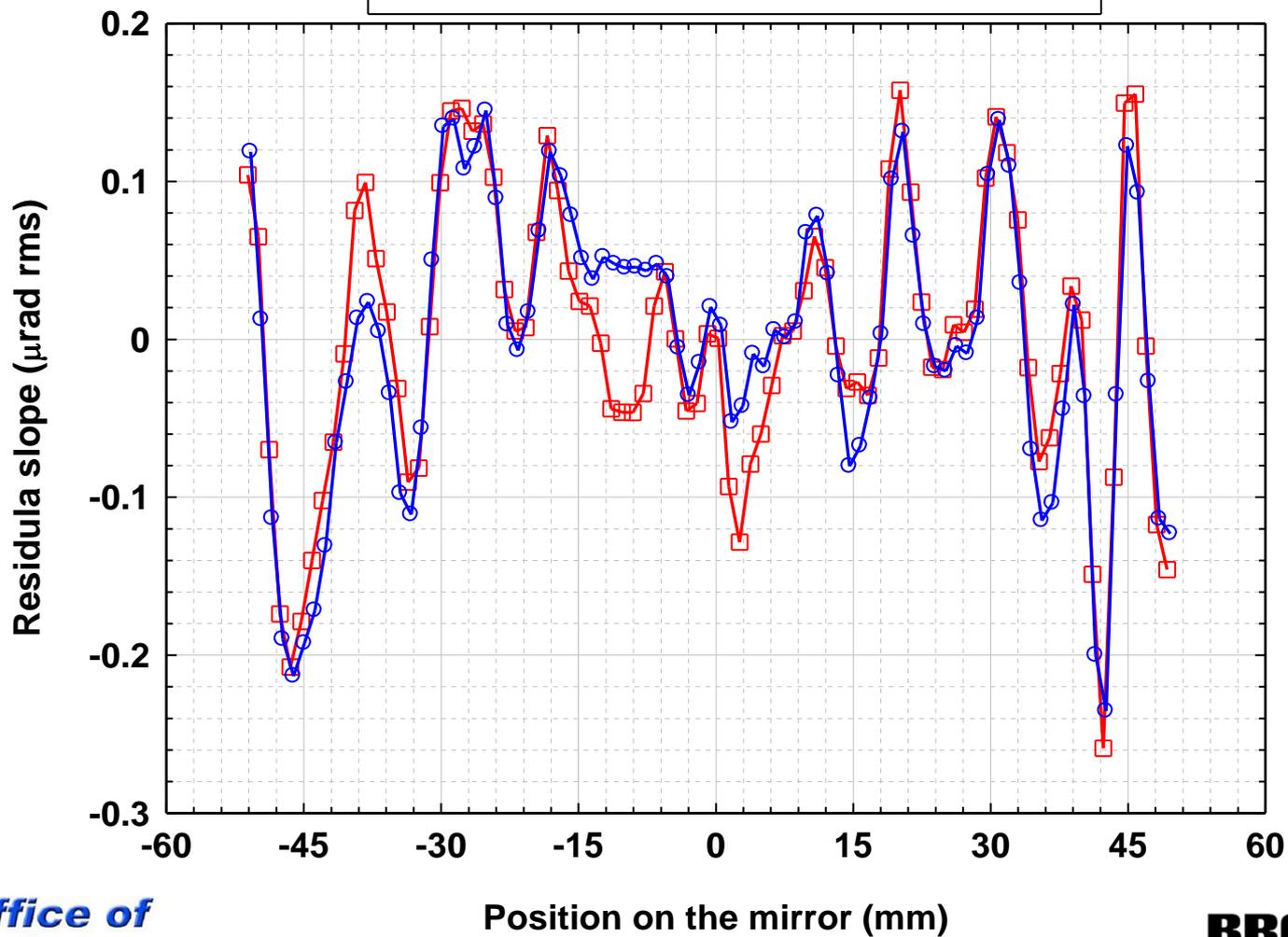
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# Some results

# Flat Silicon mirror



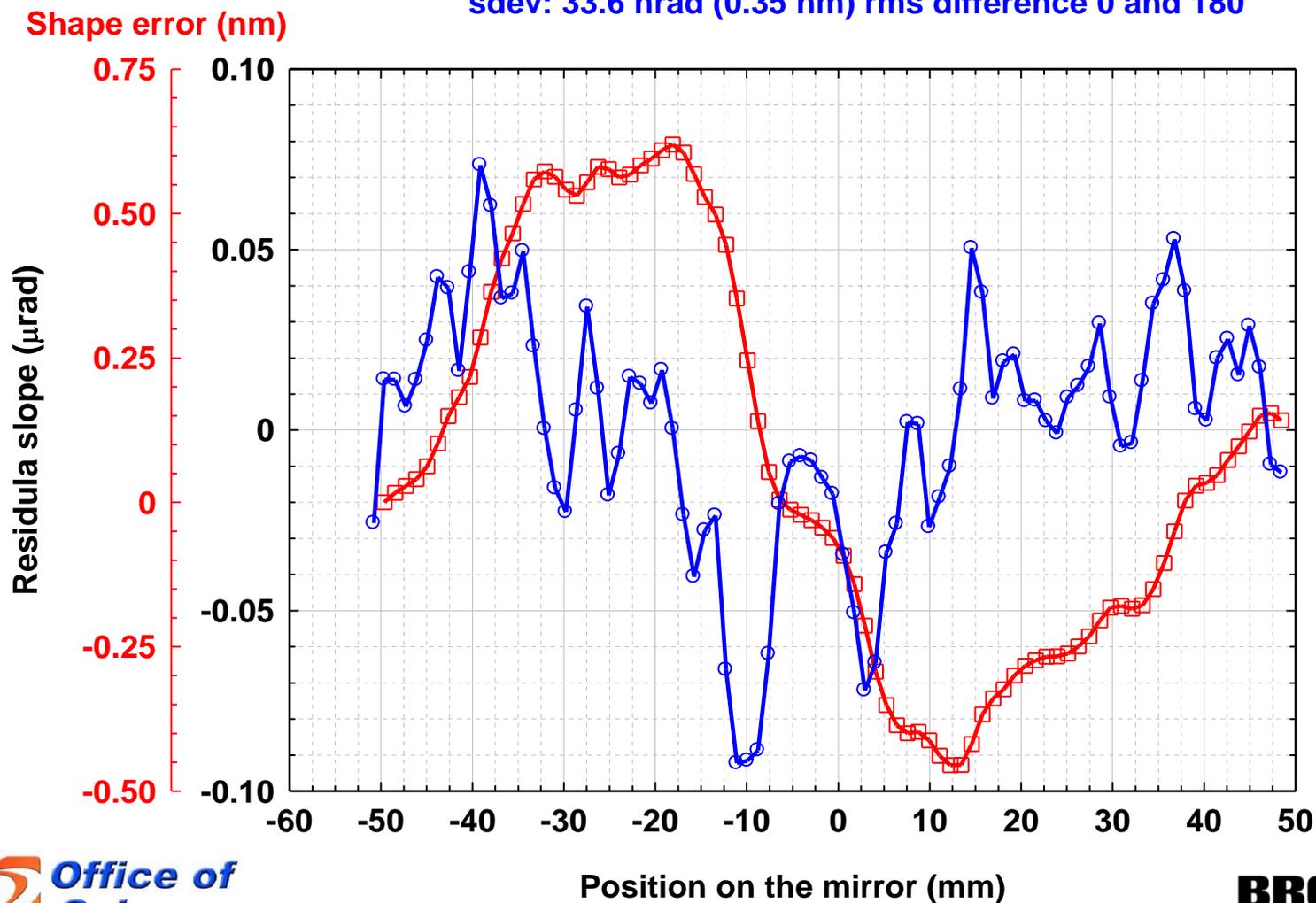
□ from A to B sdev = 88.7 nrad rms  
○ from B to A sdev = 87.9 nrad rms



# Flat Silicon mirror



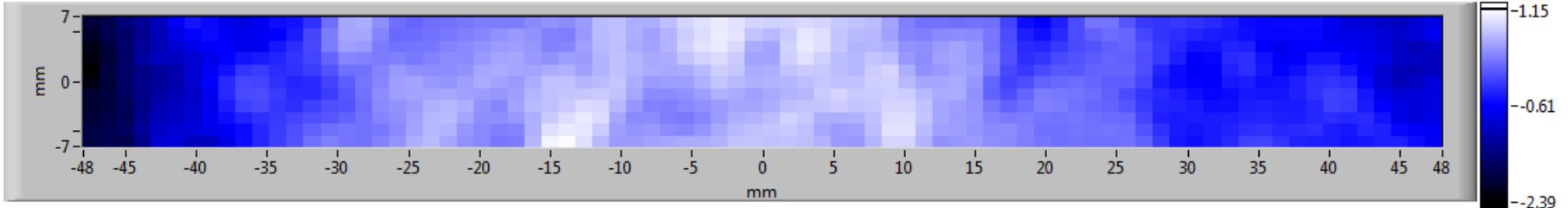
sdev: 33.6 nrad (0.35 nm) rms difference 0 and 180°



# Results on a flat mirror

Average of 26 scans on a **flat mirror** (100mm long)

Mirror Xslopes in  $\mu\text{rad}$



Slopes X rms =  $0.69\mu\text{rad}$

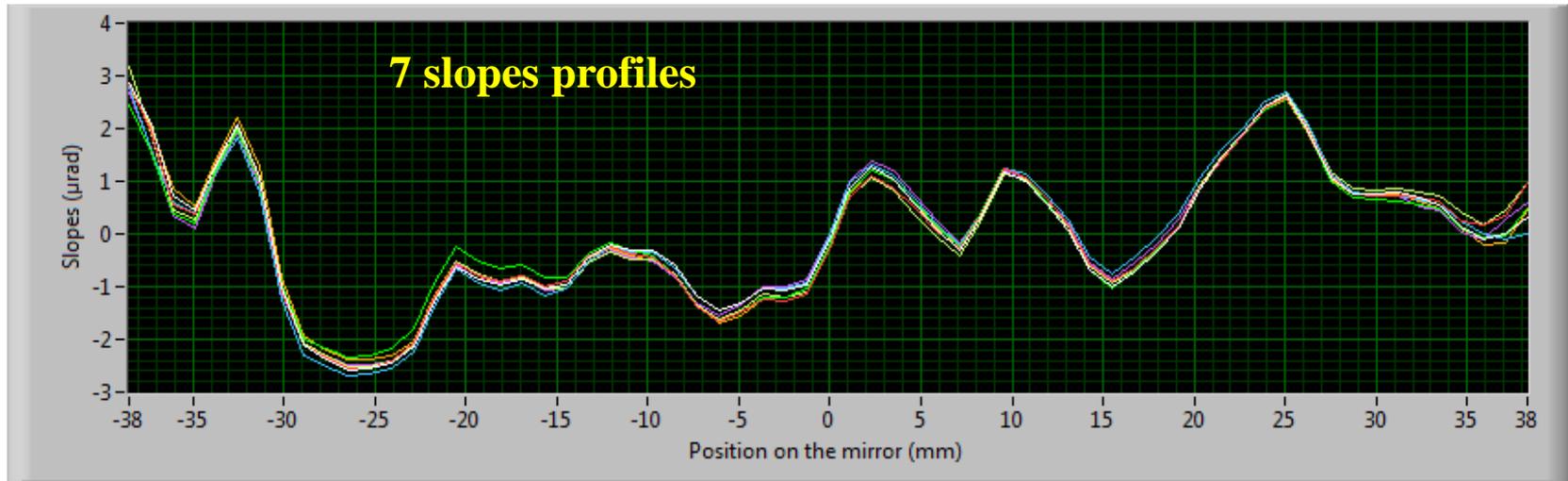
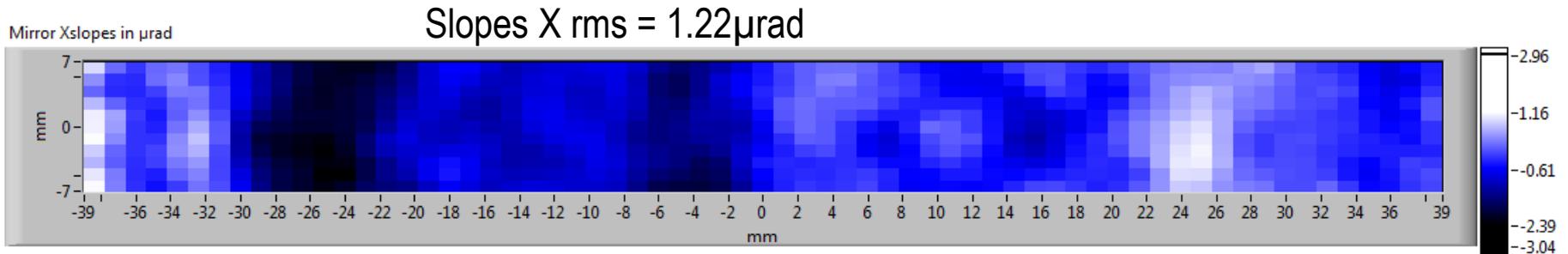


26 slopes profiles

30 nrad rms of **repeatability** obtained after subtracting best sphere

# Results on a spherical mirror (RR02)

Average of 7 scans on a spherical mirror (80mm long, **radius 55m**)



**90 nrad rms** of **repeatability** obtained after subtracting best sphere

# Preliminary results on a 1D elliptical mirror

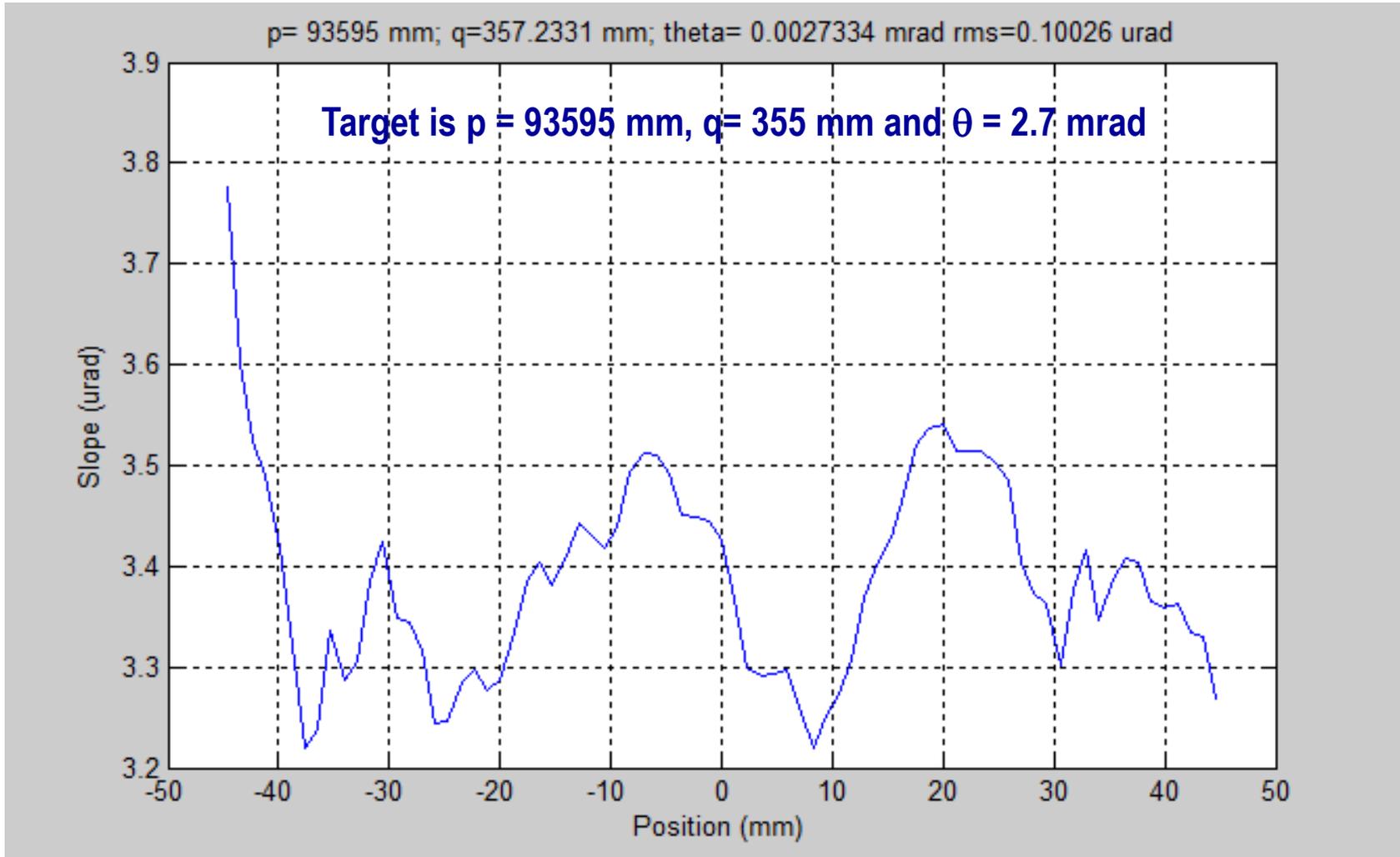
Systematic errors estimation :

same ellipse measured with angles from 0 to 1 mrad

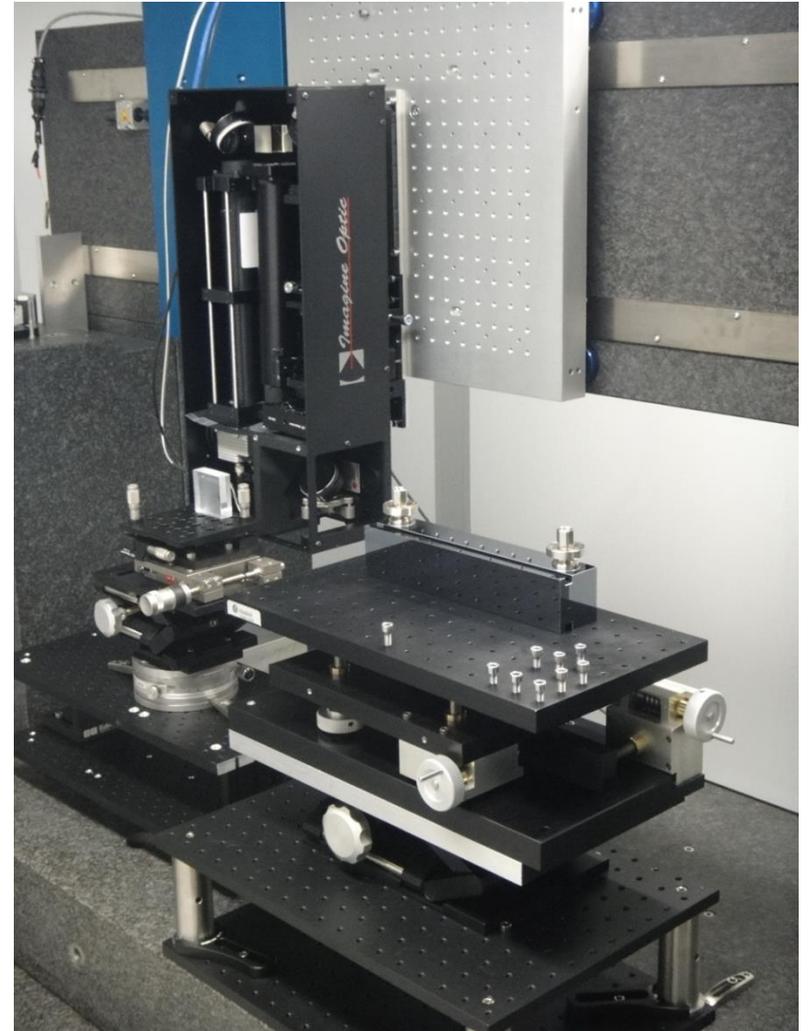


Delta slopes = 20 nrad rms

# Preliminary results on a 1D elliptical mirror

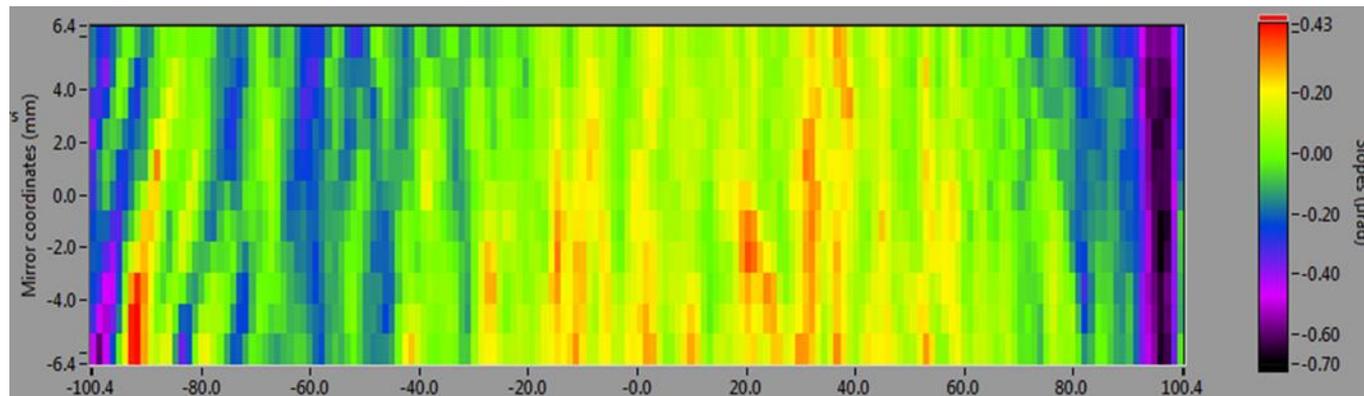


# M2A CSX



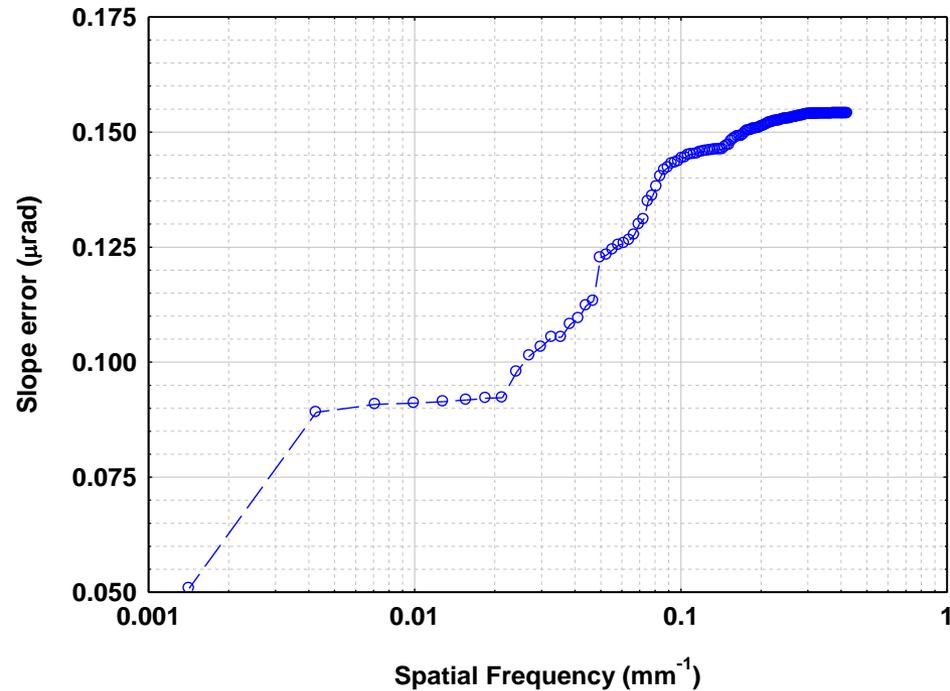
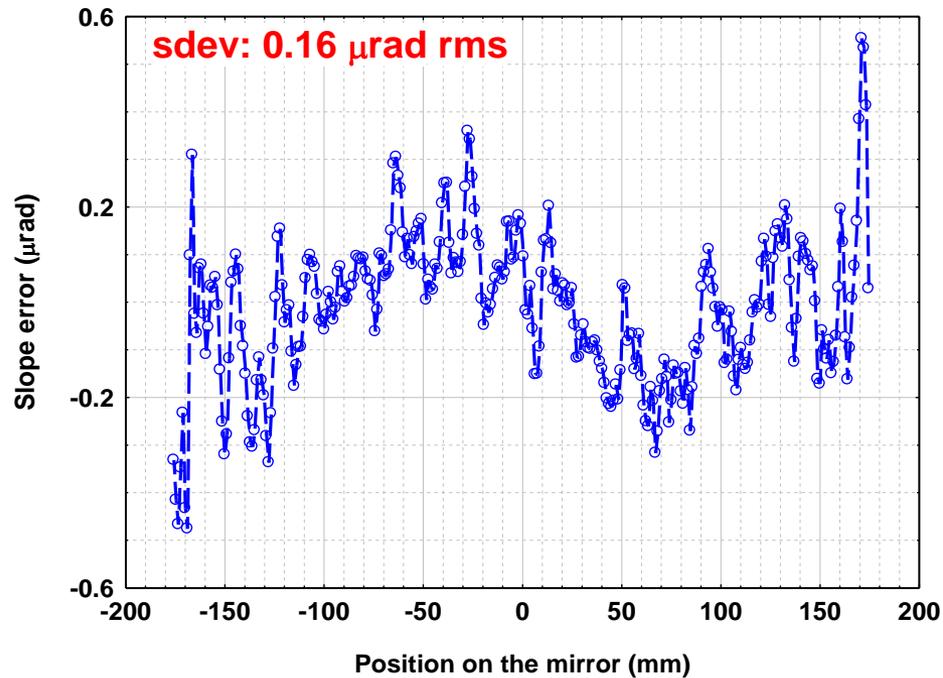
# M2A CSX

		Best radius removed	
Rx (km)	Ry (km)	X slope urad rms	Y slopes urad rms
<b>-267.16</b>	21.341	0.16	0.2



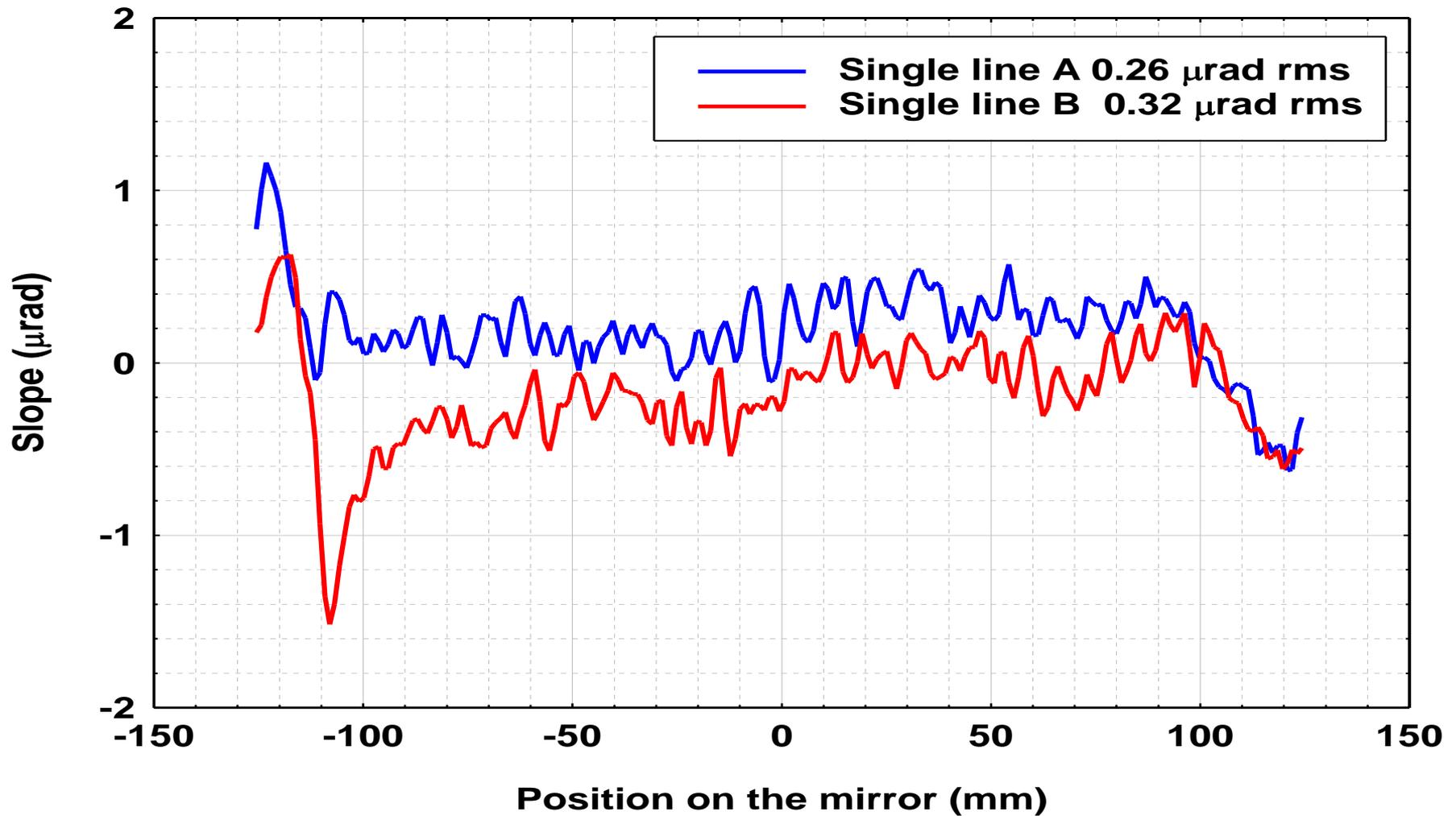
2D Map of Residual slope error of the mirror

# M2A CSX



1D Line of Residual slope error of the mirror  
and  
Integrated PSD

# Spherical mirror R~140 m CSX



# XPD mirror

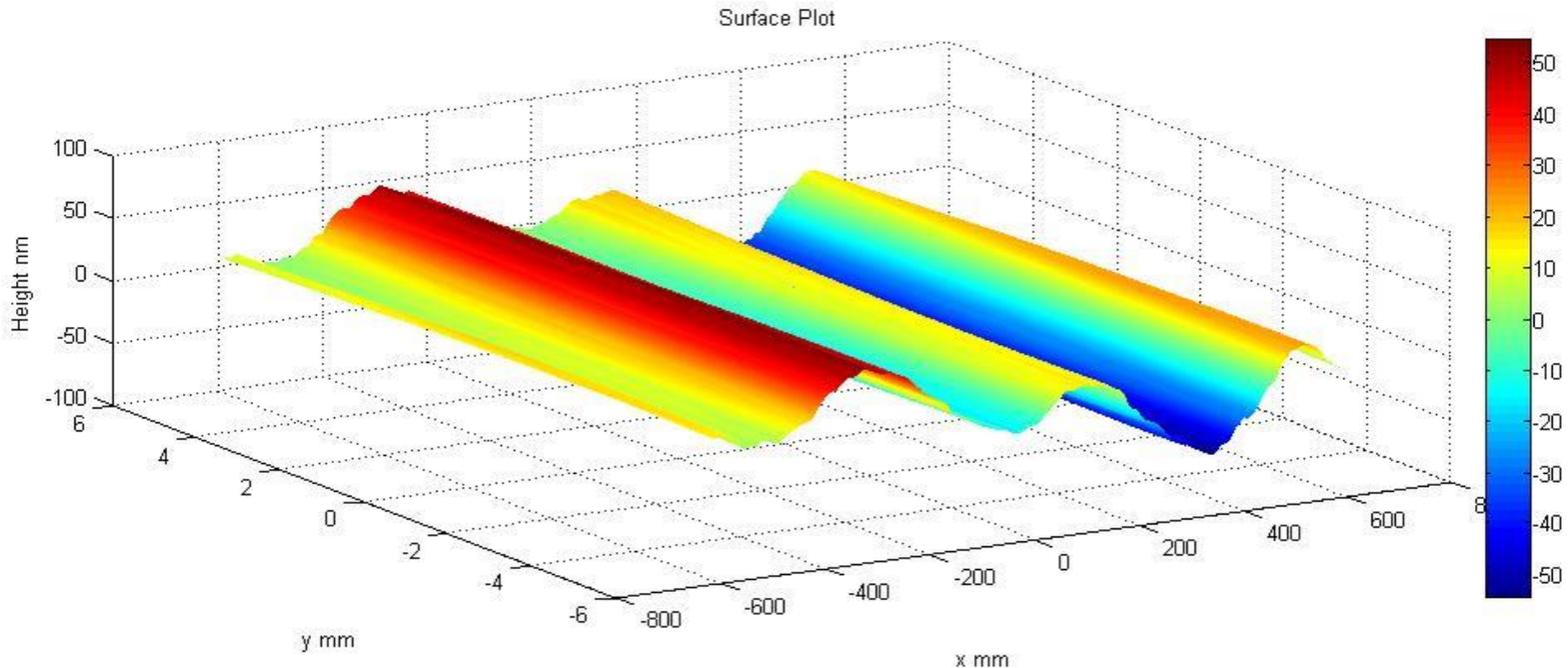


Lab E5 Mirror preparation



Lab E3 inside the enclosure

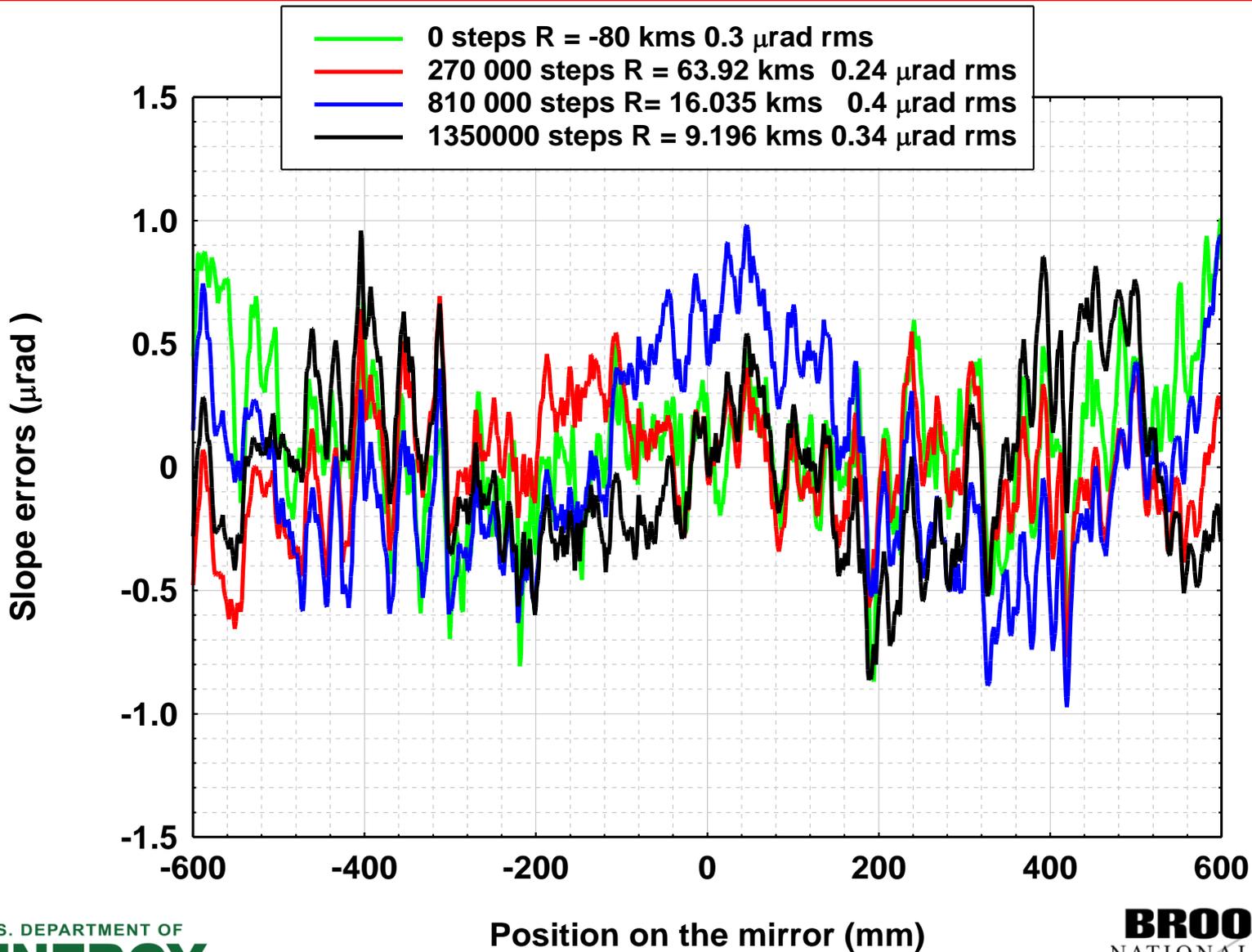
# XPD mirror



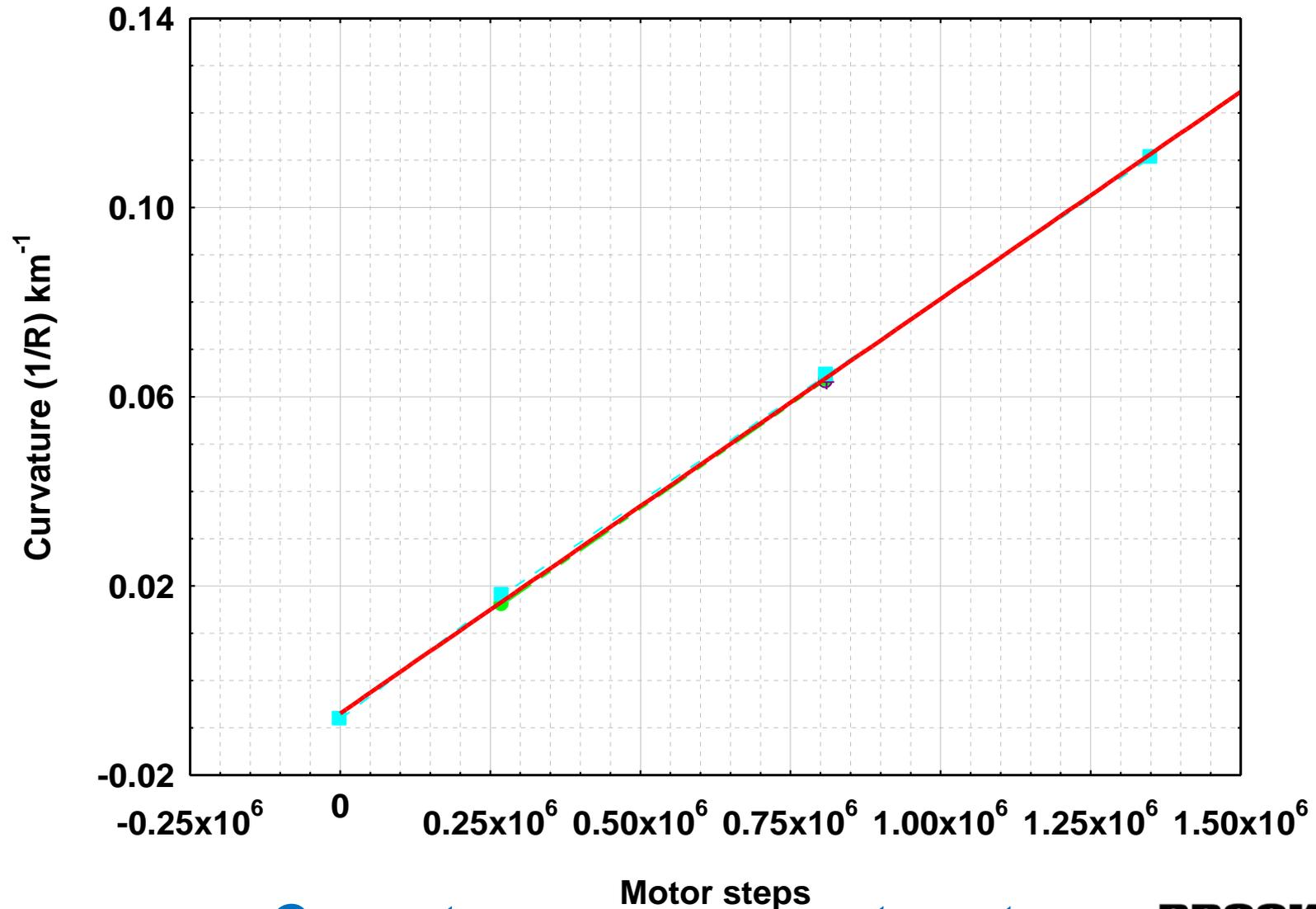
## 2D Map of Residual slope error of the mirror

*(measuring time for 1 scan Forward / Backward ~ less than 3 hours)*

# XPD mirror



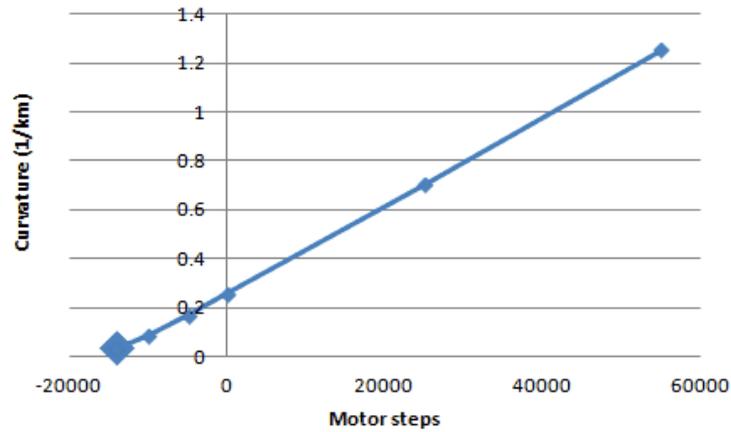
# XPD mirror



Curvature versus motor steps

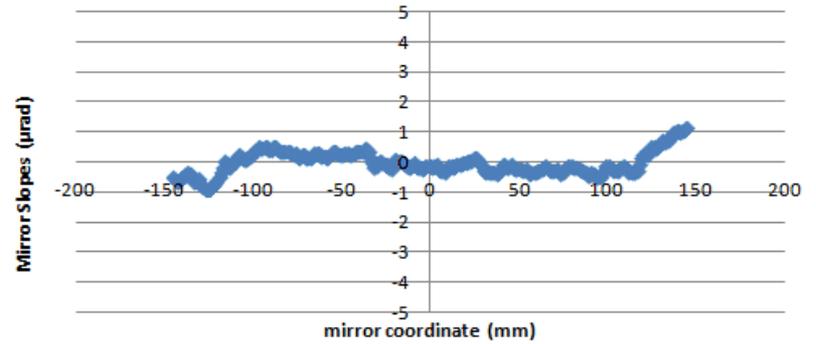
# Calibration curve

## bender CSX-M3A



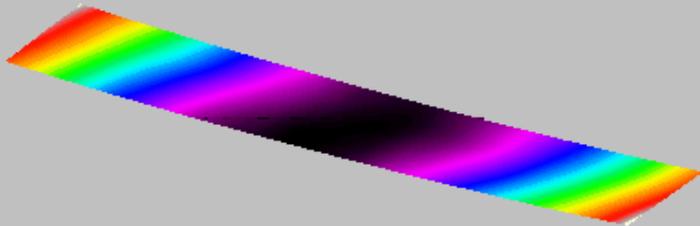
# 1D residual slope

## CSX-M3A, Rx=29.45km central line in slope



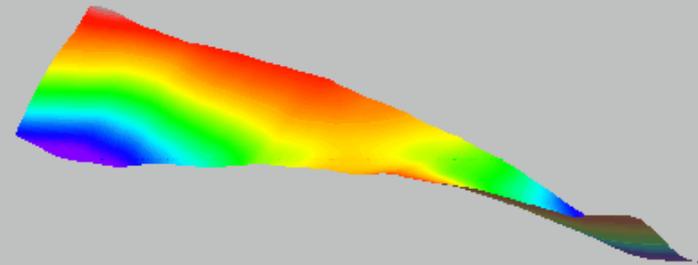
CSX-M3A : -14000 steps, Rx=29.45km

## Height



CSX-M3A : -14000 steps, Rx=29.45km

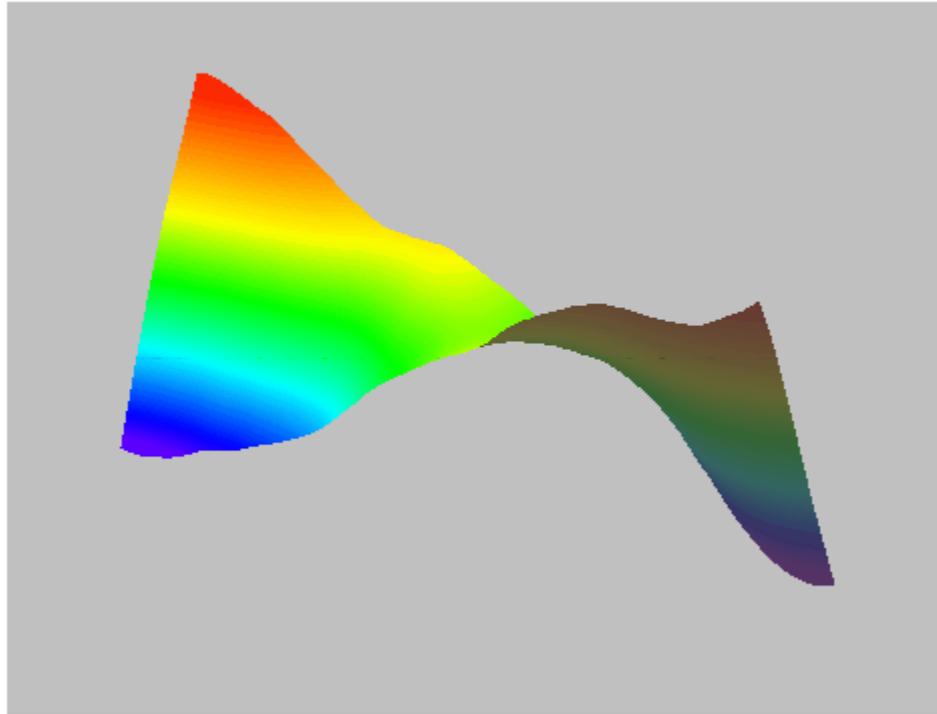
## Residual Height



# Bendable mirror after shimming

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0 microns



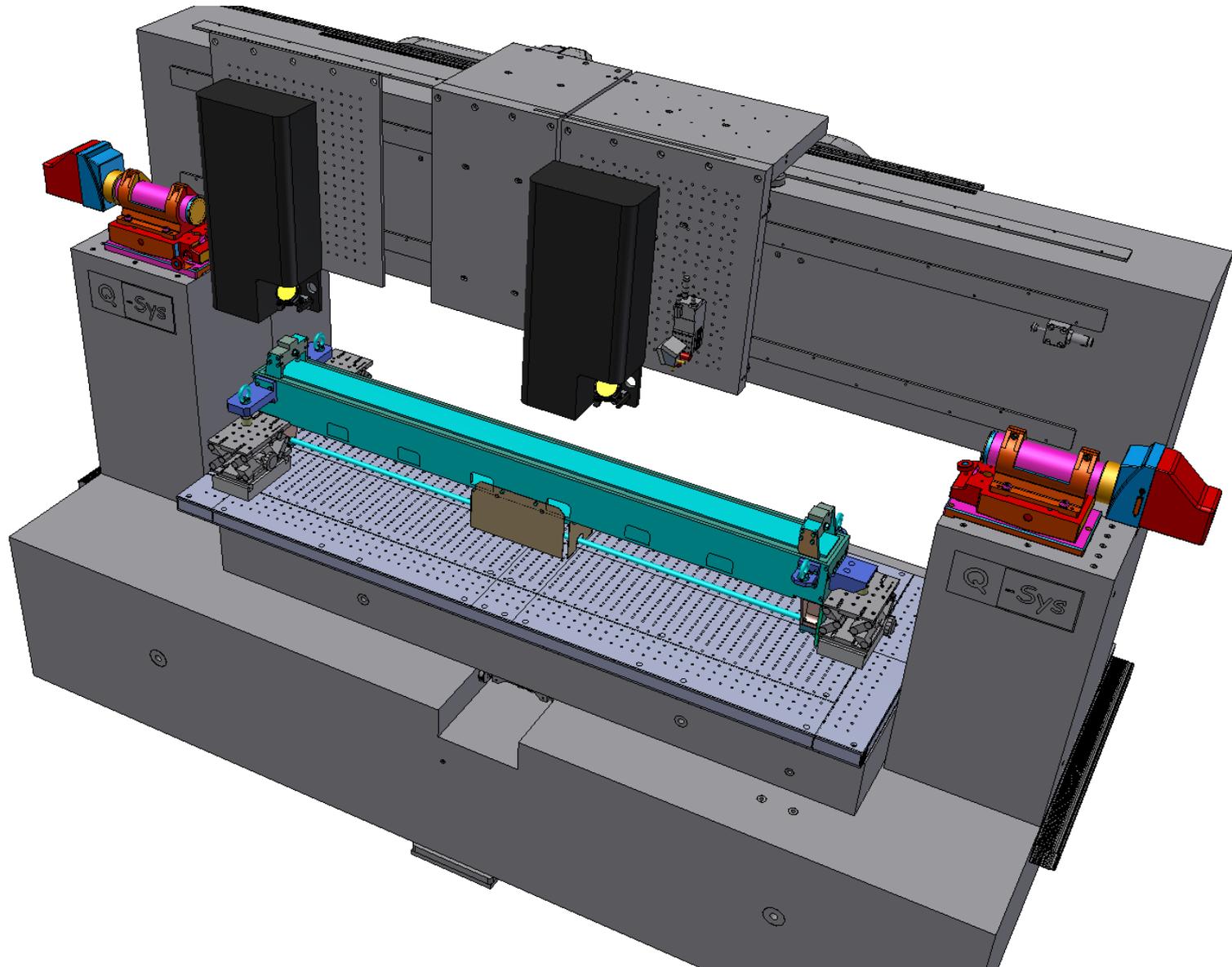
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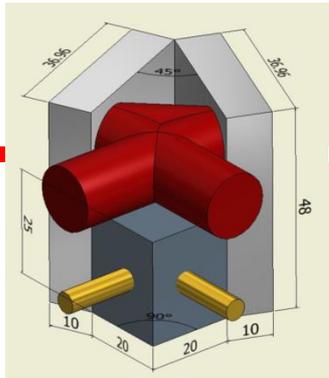
## *Possible improvements*

Depend on *Shutdown and Budget*

# Deflectometry based Optical Metrology Station

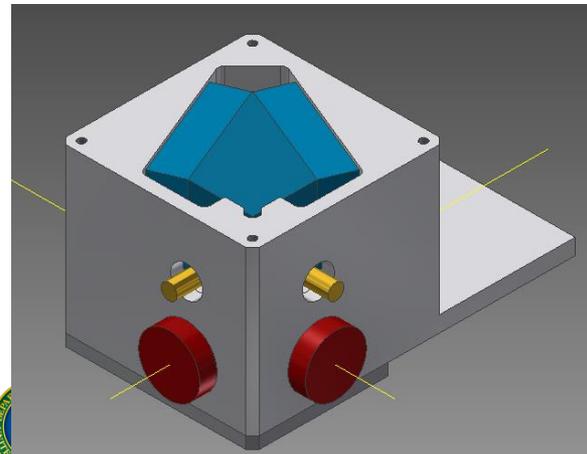
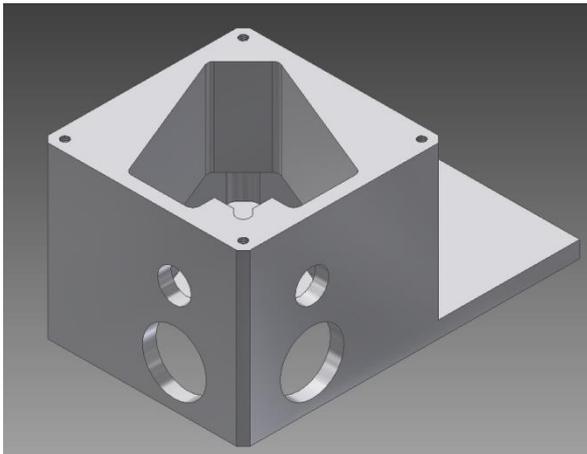
Combine several instruments in the same platform



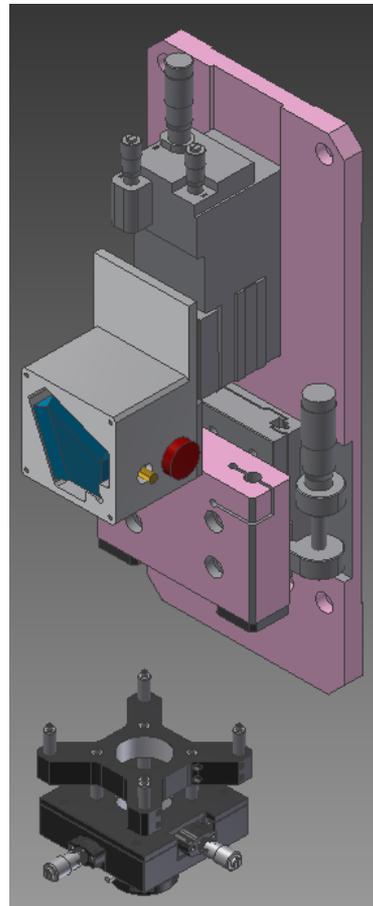


Hollow penta-prism  
20 x 20 mm

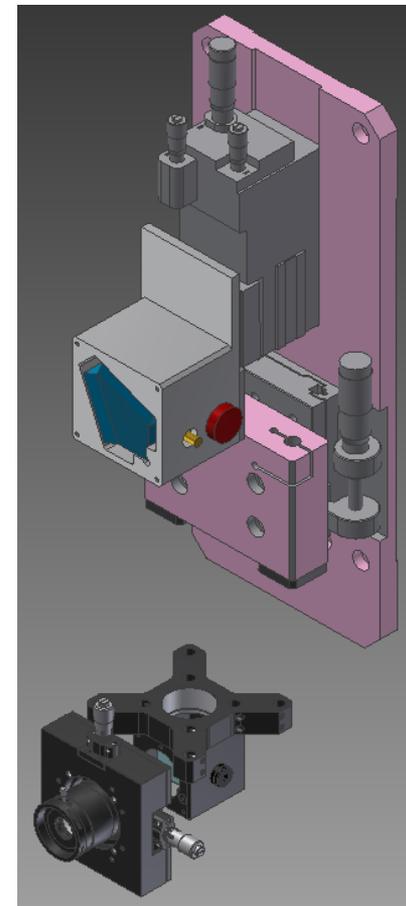
# Optical Head ~ 25 kg



VFM



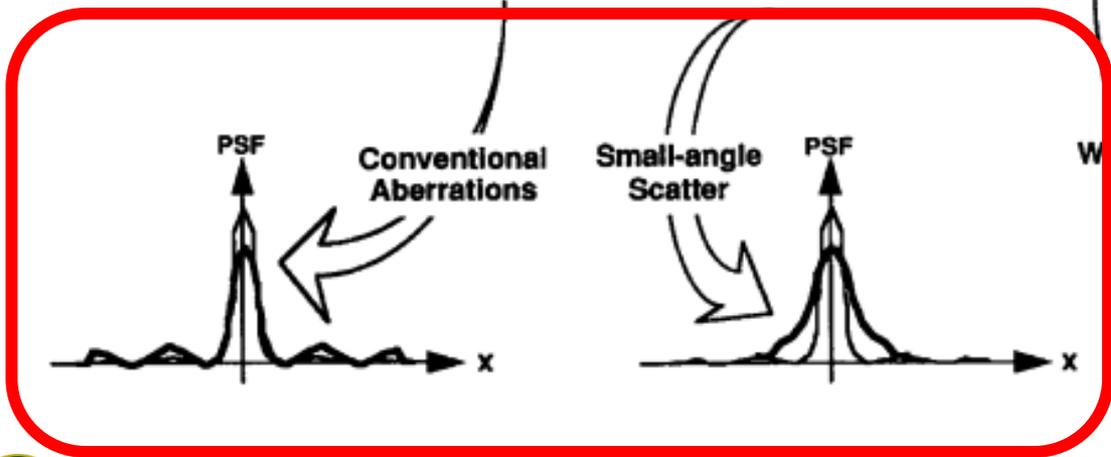
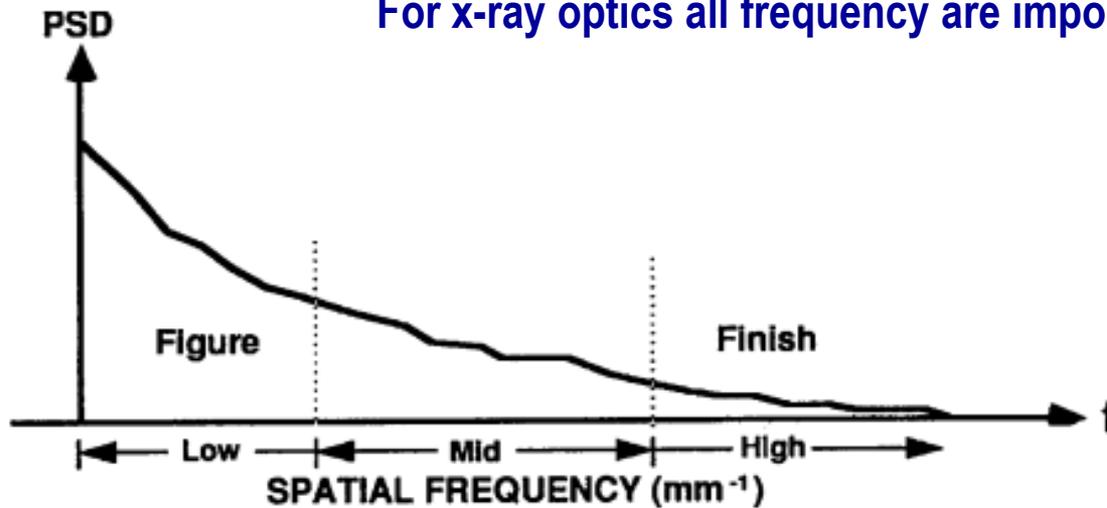
HFM



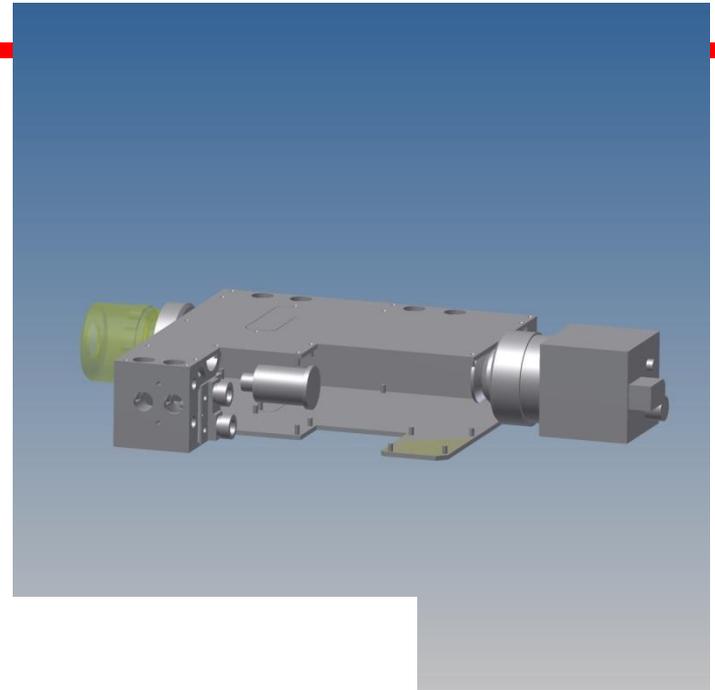
# Try to get access to higher spatial resolution

Effect of the surface quality differs on each spatial frequency regime

For x-ray optics all frequency are important

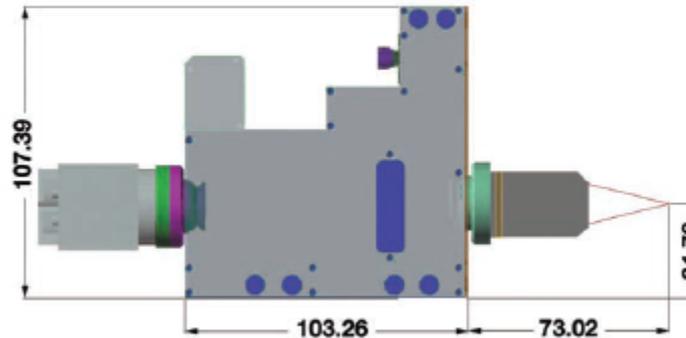


# Add another optical head for higher resolution



## Specifications

System Type	Portable, high-resolution video microscope
Probe	Phase measuring interferometer
Objectives	10X Nikon Mirau standard; 20X Mirau, or 2.5X Michelson or 5X Michelson optional
Working Distance	2.5X: 10.3 mm; 5X: 9.3 mm; 10X: 7.4 mm; 20X: 4.7 mm
Vertical Range	$\pm 6 \mu\text{m}$
RMS Repeatability	0.05 nm
RMS Precision	0.1 nm
Sample Reflectivity	4–98%



MFT probe.

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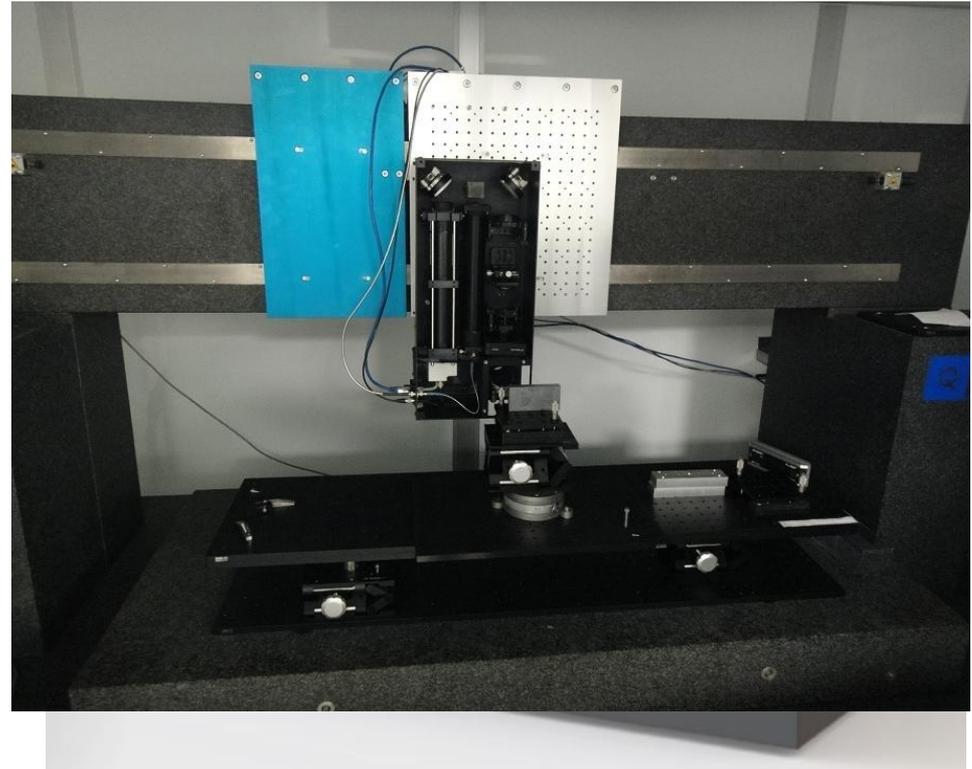
# Add another optical head still based on a SH wavefront sensor with higher spatial resolution

## Main advantages

- Same measuring points for both instruments
- “Easy” integration in the existing hardware and software
- Try to reach smaller radius of curvature / toroidal mirrors

# CONCLUSION

Shack-Hartmann Wavefront sensor	
Number of points	15 x 11
Pupil size	18 x 13 mm
Microlenses size Resolution	1.2x1.2 mm <sup>2</sup>
Measurement range	From 5 mm to 1500 mm
Radius of curvature	From -1.2 m to 1.2 m
Sensitivity	Better than 50 nrad rms



# Acknowledgements

## Optical Metrology Group

Shinan Qian - Konstantine Kaznatcheev

## Optical Fabrication Group Ray Conley + his Group

Wayne Lewis - Oksana Ivashkevych - So Sung-Leung

Daniel Bacescu (CSX Beamline) - Scott Coburn (IXS Beamline)

Josep Nicolas (ALBA)  
Frank Siewert (Bessy)  
Kawal Sawhney (DIAMOND)  
Lahsen Assoufid (APS)



Muriel Thomasset  
Pascal Mercere  
Francois Polack



Samuel Bucourt - Xavier Levecq  
Jerome Legrand - Rakchanok RUNGSAWANG  
Mathias Bach



Henry Over  
Philipp Wallington

Research supported by U.S. Department of Energy, Office of Basic Energy Sciences  
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# THANK YOU FOR YOUR ATTENTION

# SHARP<sub>eR</sub>

EUROSTARS PROJECT 13202



*Imagine Optic*

**NEW HIGH ACCURACY SURFACE METROLOGY PLATFORM  
SYSTEM FOR HIGH QUALITY MIRROR CHARACTERIZATION  
SLOPE ACCURACY BETTER THAN 50 NRAD RMS**

